FORM PTO-1449		SERIAL NO.	CASE NO.
		10/577,175	9905/40 (BIF116533US)
LIST OF PATENTS AN	PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION	I DISCLOSURE STATEMENT	April 3, 2007	2813
(use several sheets if necessary)	APPLICANT(S): Nguyet-Phuon	a Namon et el	CONFIRMATION NO.
(use several sileets if flecessary)	AFFLICANT(3). Nguyet-Friuon	ig nguyen et al.	3451

EXAMINER INITIAL		DOCUMENT NUMBER Number-Kind Code (if known)	DATE	NAME	CLASS/ SUBCLASS	FILING DATE
	D1	3.901.423	08/1975	Hillberry, et al.		
	D2	3.915.757	10/1975	Engel		
	D3	3.957.107	05/1976	Altoz et al.		
	D4	3,993,909	11/1976	Drews et al.		
	D5	4.006,340	02/1977	Gorinas		
_	D6	4.039.416	08/1977	White		_
	D7	4,074,139	02/1978	Pankove		
	D8	4,107,350	08/1978	Berg et al.		
	D9	4.108.751	08/1978	King		
	D10	4,121,334	10/1978	Wallis		
	D11	4,170,662	10/1979	Weiss et al.		
	D12	4,179,324	12/1979	Kirkpatrick		
	D13	4,244,348	01/1981	Wilkes		
	D14	4,252,837	02/1981	Auton		
	D15	4,274,004	06/1981	Kanai		
	D16	4,324,631	08/1982	White et al.		
	D17	4.346.123	08/1982	Kaufmann		
	D18	4,361,600	11/1982	Brown		
	D19	4,368,083	01/1983	Bruel et al.		
	D20	4,412,868	11/1983	Brown et al.		
	D21	4,452,644	06/1984	Bruel et al.		
	D22	4,468,309	08/1984	White		
	D23	4,471,003	09/1984	Cann		
	D24	4,486,247	12/1984	Ecer et al.		
	D25	4,490,190	12/1984	Speri		
	D26	4,500,563	02/1985	Ellenberger et al.		
	D27	4,508,056	04/1985	Bruel et al.		
	D28	4,536,657	08/1985	Bruel		
	D29	4,539,050	09/1985	Kramler et al.		
	D30	4,542,863	09/1985	Larson		
	D31	4,566,403	01/1986	Fournier		
	D32	4,567,505	01/1986	Pease		
	D33	4,568,563	02/1986	Jackson et al.		
	D34	4,585,945	04/1986	Bruel et al.		
	D35	4,630,093	12/1986	Yamaguchi et al.		
	D36	4,684,535	08/1987	Heinecke et al.		
	D37	4.704.302	11/1987	Bruel et al.		

EXAMINER DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /DL/

						Page 2 of 4
FORM PTO-14	49			SERIAL NO.		CASE NO.
				10/57	7,175	9905/4
LICT OF	DATEN	ITS AND PUBLICATIO	NC FOR	FILING DATE		(BIF116533US GROUP ART UNIT
		INFORMATION DISCL		April 3, 2007		281
ALLEG		STATEMENT	OUUNE	74711 0, 2007		201
use several sh	eets if			APPLICANT(S): Nguyet-F	huong	Nguyen et al.
	D00	4 747 000	01/1988	Parrillo et al.		
	D38	4,717,683			-	
	D39	4,764,394	08/1988	Conrad	-	
	D40	4,837,172	06/1989	Mizuno et al.	-	
	D41	4,846,928	07/1989	Dolins et al.	_	
	D42	4,847,792	07/1989	Barna et al.	1-	
	D43	4,853,250	08/1989	Boulos et al.		
	D44	4,887,005	12/1989	Rough et al.	1	
	D45	4,891,329	01/1990	Reisman et al.	1	
	D46	4,894,709	01/1990	Phillips et al.		
	D47	4,904,610	02/1990	Shyr		
	D48	4,920,396	04/1990	Shinohara et al.		
	D49	4,929,566	05/1990	Beitman		
	D50	4,931,405	06/1990	Kamijo et al.		
	D51	4,948,458	08/1990	Ogle		
	D52	4,952,273	08/1990	Popov	1	
	D53	4,956,698	09/1990	Wang		
	D54	4,960,073	10/1990	Suzuki et al.		
	D55	4,975,126	12/1990	Margail et al.	1	
	D56	4,982,090	01/1991	Wittmaack		
	D57	4,996,077	02/1991	Moslehi et al.	1	
	D58	5,013,681	05/1991	Godbey et al.		
	D59	5,015,353	05/1991	Hubler et al.		
	D60	5.034.343	07/1991	Rouse et al.		
	D61	5,036,023	07/1991	Dautremont-Smith et al.	-	
	D62	5,110,748	05/1992	Sarma		
	D63	5.120.666	06/1992	Gotou		
	D64	5,138,422	08/1992	Fujii et al.	-	
	D65	5,198,371	03/1993	Li	 	
	D66	5,200,805	04/1993	Parsons et al.		
	D67	5,232,870	08/1993	Ito et al.	-	
	D68	5,234,535	08/1993	Beyer et al.	\vdash	
	D69	5,250,446	10/1993	Osawa et al.	\vdash	
	D70	5,256,581	10/1993	Foerstner et al.	-	
	D71	5,259,247	11/1993	Bantien	 	
	D71	5,310,446	05/1994	Konishi et al.	 	
	D73	5,413,951	05/1994	Ohori et al.	 	
	D73				_	
		5,442,205	08/1995	Brasen et al.	\vdash	
	D75	5,494,835	02/1996	Bruel	₩	
	D76	5,524,339	06/1996	Gorowitz et al.	₩	
	D77	5,539,241	07/1996	Abidi et al.	<u> </u>	
	D78	5,567,654	10/1996	Beilstein, Jr. et al.	1	
	D79	5.611.316	03/1997	Oshima et al.		

ORM PTO-1449			SERIAL NO.	10/577,175	CASE NO. 9905/4
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT use several sheets if necessary)				10/0//,1/0	(BIF116533US
		FILING DATE	April 3, 2007	GROUP ART UNIT 281	
		APPLICANT(S): Nguyet-Phuong Nguyen et al.			
D80	5.618.739	04/1997	Takahashi et al.		
D81	5.622.896	04/1997	Knotter et al.		
D82	5,633,174	05/1997	Li		
D83	5,661,333	08/1997	Bruel et al.		
D84	5,714,395	02/1998	Bruel		
D85	5,741,733	04/1998	Bertagnolli et al.		
D86	5,753,038	05/1998	Vichr et al.		
D87	5,804,086	09/1998	Bruel		
D88	5,817,368	10/1998	Hashimoto		
D89	5,863,830	01/1999	Bruel et al.		
D90	5.863.832	01/1999	Doyle et al.		
D91	5,880,010	03/1999	Davidson		
D92	5,882,987	03/1999	Srikrishnan		
D93	5,897,331	04/1999	Sopori		
D94	5,981,400	11/1999	Lo		
D95	5.985.412	11/1999	Gösele		
D96	6,010,591	01/2000	Gösele		
D97	6,013,954	01/2000	Hamajima		
D98	6.020,252	02/2000	Aspar et al.		
D99	6.033.974	03/2000	Henley et al.		
D100		04/2000	Sakaguchi et al.		
D10		05/2000	Chan et al.		
D10:		06/2000	Gardner et al.		
D10:		08/2000	Kikuchi et al.		
D104		09/2000	Merchant et al.		
D10:		12/2000	Shimada et al.		
	6 6.159.323	12/2000	Joly et al.		
D10		03/2001	Joly et al.		
D108		03/2001	Hosoma et al.		
D109		03/2001	Yamagata et al.		
D110		03/2001	Aspar et al.		
D11		05/2001	Aspar et al.		
D11:		06/2001	Ohshima et al.		
D113		08/2001	Nelson et al.		
D114		09/2001	Cole et al.		
D11		09/2001	Shkaguchi et al.		
D110		10/2001	Dina		
D11		10/2001	Seefeldt et al.		
D11		11/2001	Bruel et al.		
D11		03/2002	Doyle et al.		
D12		06/2002	Hale et al.		
D12		07/2002	Haberger et al.		

Page 4 of 48

LIST OF PATEN				10/577,175	9905/4 (BIF116533US
LIST OF PATENTS AND PUBLICATIONS APPLICANT'S INFORMATION DISCLOS STATEMENT			FILING DATE	April 3, 2007	GROUP ART UNIT 281
use several sheets if			APPLICANT(S): N	guyet-Phuong	Nguyen et al.
	6,429,094 B1	08/2002	Maleville et al.		
D123		08/2002	Auberton-Herve		
D124		10/2002	Suga		
D125		01/2003	Schmitz et al.		
D126	6,529,646 B1	03/2003	Wight et al.		
D127	6,548,375 B1	04/2003	De Los Santos et	al.	
D128	6,596,569 B1	07/2003	Bao et al.		
D129	6,632,082 B1	10/2003	Smith		
D130	6,645,831 B1	11/2003	Shaheen et al.		
D131	6,645,833 B2	11/2003	Ohya et al.		
D132	6,653,207 B2	11/2003			
D133	6,756,285 B1	06/2004	Moriceau et al.	_	
D134	6,762,076 B2		Kim et al.		
D135	6,764,936 B2	07/2004	Daneman et al.		
D136	6,774,010 B2	08/2004	Chu et al.	_	
D137	6,809,009 B2	10/2004	Aspar et al.		
D138	6,828,214 B2	12/2004	Notsu et al.		+-
	6,846,690 B2		Kellar et al.		
D140	6,887,769 B2 6,893,936 B1	05/2005	Chen et al.		
		05/2005	Tong et al.		
D142	6,902,987 B1 6,927,147 B2	08/2005	Fitzgerald et al.		
D143	6,927,147 B2 6,947,365 B2	09/2005	Lai et al.		
D144 D145		12/2005	Moriceau et al.		
D145					
D146	6,991,956 B2 7.018,909 B2	01/2006	Ghyselen et al. Ghyselen et al.		
D147	7,018,909 B2 7,029,548 B2	03/2006	Aspar et al.		
D148		04/2006	Liu et al.		
D149	7,029,980 B2 7,067,396 B2	06/2006	Aspar et al.		
D150	7,078,811 B2	07/2006	Suga		
D151		08/2007	Ghyselen et al.		
D152	7,256,075 B2 7,348,260 B2	03/2008	Ghyselen et al.		
D153	7,348,260 B2 7,416,957 B2	08/2008	Ponomarev	_	
D155	7,410,937 B2 7,459,374 B2	12/2008	Aulnette et al.		
D156	7,459,574 B2 7,465,646 B2	12/2008	Le Vaillant		
D156	7,476,596 B2	01/2009	Lieber et al.		
D157	7,476,596 B2 7,494,897 B2	02/2009	Fournel et al.		
D158	7,494,897 B2 7,498,234 B2	03/2009	Aspar et al.		
D159		03/2009	Rogers et al.	_	
D160	7,534,701 B2	05/2009	Ghyselen et al.		
D161	7,534,701 B2 7,615,463 B2	11/2009	Aspar et al.	_	
D163	7,670,930 B2	03/2010	Tauzin et al.		

Page 5 of 48

FORM PTO-1449			SERIAL NO.		CASE NO.
				10/577,175	9905/40
					(BIF116533US)
	NTS AND PUBLICATION		FILING DATE		GROUP ART UNIT
APPLICANT'S	INFORMATION DISC	LOSURE		April 3, 2007	2813
STATEMENT		A DDI IO A NIT(O)	N DI	N	
(use several sheets i	r necessary)		APPLICANT(S):	Nguyet-Phuon	j Nguyen et al.
D164	7,713,369 B2	05/2010	Aspar et al.		
D165	7,772,087 B2	08/2010	Nguyen et al.		
D166	7,883,994 B2	02/2011	Moriceau et al.		
D167	7,902,038 B2	03/2011	Aspar et al.		
D168	RE39,484 E	02/2007	Bruel		
D169	2001/0007367 A1	07/2001	Ohkubo		
D170	2001/0007789 A1	07/2001	Aspar et al.		
D171	2002/0000646 A1	01/2002	Gooch et al.		
D172	2002/0081861 A1	06/2002	Robinson et al.		
D173	2002/0145489 A1	10/2002	Cornett et al.		
D174	2002/0185469 A1	12/2002	Podlesnik et al.		
D175	2002/0083387 A1	06/2002	Miner et al.		
D176	2002/0001221 A1	01/2003	Fischer et al.		
D177	2003/0119279 A1	06/2003	Enquist		
D178	2003/0119280 A1	06/2003	Lee et al.		
D179	2005/0148163 A1	07/2005	Nguyen et al.		
D180	2006/0252229 A1	11/2006	Joly et al.		
D181	2006/0281212 A1	12/2006	Moriceau et al.		
D182		02/2007	Aspar et al.		
D183		10/2008	Deguet et al.		
D184		05/2009	Deguet et al.		
D185		05/2009	Aspar et al.		
D186		06/2009	Di Cioccio		
D187		02/2010	Tauzin et al.		
D188		07/2010	Fournel et al.		
D189		08/2010	Rabarot et al.		
D190	2010/0323497 A1	12/2010	Fournel		

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER Number-Kind Code (if known)	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES OR NO
	D191	EP 0 355 913 A1	02/1990	EPO		
	D192	EP 0 383 391 A1	08/1990	EPO		
	D193	EP 0 504 714 A2	09/1992	EPO		
	D194	EP 0 660 140 A1	06/1995	EPO		ABSTRACT
	D195	EP 0 665 588 A1	08/1995	EPO		ABSTRACT
	D196	EP 0 703 609 A1	03/1996	EPO		ABSTRACT
	D197	EP 0 754 953 B1	01/1997	EPO	1	ABSTRACT
	D198	EP 0 849 788 A2	06/1998	EPO		
	D199	EP 0 889 509 A2	01/1999	EPO		
	D200	EP 0 895 282 A2	02/1999	EPO	1	
	D201	EP 0 898 307 A1	02/1999	EPO		ABSTRACT

EXAMINER DATE CONSIDERED EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609;

Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-1449

FORW F 10-1449			SERIAL NO.	10/577,175	9905/4
				10/0/7,170	(BIF116533US
	TS AND PUBLICATION		FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE STATEMENT				April 3, 2007	
use several sheets if n	ecessary)		APPLICANT(S):	Nguyet-Phuong	Nguyen et al.
D202	EP 0 989 593 A2	03/2000	I EPO		
D203	EP 1 059 663 A2	12/2000	EPO		
D204	EP 1 096 259 A1	05/2001	EPO		
D205	DE 101 53 319 A1	05/2003	GERMANY		ABSTRACT
D206	FR 95 08882	06/1996	FRANCE		ABSTRACT
D207	FR 2 558 263 A1	07/1985	FRANCE		ABSTRACT
	FR 2 671 472 A1	07/1992	FRANCE		ABSTRACT
D209	FR 2 725 074 A1	03/1996	FRANCE		ABSTRACT
D210	FR 2 736 934 A1	01/1997	FRANCE		ABSTRACT
D211	FR 2 767 604 A1	02/1999	FRANCE		ABSTRACT
D212	FR 2 771 852 A1	06/1999	FRANCE		ABSTRACT
D213	FR 2 789 518 A1	08/2000	FRANCE		ABSTRACT
D214	FR 2 819 099 A1	07/2002	FRANCE		ABSTRACT
D215	GB 2 211 991 A	07/1989	GREAT BRITAI	N	
D216	JP 53-104156 A	09/1978	JAPAN		ABSTRACT
D217	JP 58-031519 A	02/1983	JAPAN		ABSTRACT
D218	JP 59-054217 A	03/1984	JAPAN		ABSTRACT
D219	JP 61-129872 A	06/1986	JAPAN		ABSTRACT
D220	JP 01-128570 A	05/1989	JAPAN		ABSTRACT
D221	JP 01-169917 A	07/1989	JAPAN		ABSTRACT
D222	JP 04-199504 A	07/1992	JAPAN		ABSTRACT
D223	JP 08-017777 A	01/1990	JAPAN		ABSTRACT
D224	JP 08-133878 A	05/1996	JAPAN		ABSTRACT
D225	JP 10-163166 A	06/1998	JAPAN		ABSTRACT
D226	JP 10-233352 A	09/1998	JAPAN		ABSTRACT
D227	JP 11-317577 A	11/1999	JAPAN		ABSTRACT
D228	SU 128757 A1	06/2000	RUSSIA		ABSTRACT
D229	WO 95/20824 A1	08/1995	WIPO		ABSTRACT
D230	WO 01/43168 A2	06/2001	WIPO		ABSTRACT
D231	WO 02/05344A1	01/2002	WIPO		ABSTRACT
D232	WO 03/021667 A2	03/2003	WIPO		
D233	WO 03/063213 A2	07/2003	WIPO		

SERIAL NO.

EXAMINER INITIAL		OTHER ART — NON PATENT LITERATURE DOCUMENTS le name of author, tide of the article (when appropriate), title of the itien (book, magazine, journal, serial, ssium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.
	D234	Agarwal, Aditya et al. "Efficient Production of Silicon-On-Insulator Films by Co- Implantation of He* with H** – Proceedings 1997 IEEE International SOI Conference, October 1997 – pp. 44-45.
	D235	Ahn, K. Y., et al., "Growth, Shrinkage, And Stability of Interfacial Oxide Layers Between Directly Bonded Silicon Wafers", <i>Applied Physics A.</i> , Vol. 50, 1990, pp 85-94.

EXAMINER DATE CONSIDERED

		Page 7 of 48	
FORM PTO-1449	SERIAL NO.	CASE NO.	
	10/577,175	9905/40	
		(BIF116533US)	
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT	
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813	
STATEMENT			
(use several sheets if necessary)	se several sheets if necessary) APPLICANT(S): Nouvet-Phyong Nouven et al.		

	_	
EXAMINER	0	OTHER ART – NON PATENT LITERATURE DOCUMENTS le name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial,
INITIAL	sympo	sium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.
	D236	Alley et al., "Surface Roughness Modification of Interfacial Contacts In Polysilicon
		Microstructures", Proceedings of the 7th International Conference on Solid-State
		Sensors and Actuators. Transducers '93. PACIFICO, Yokohama JAPAN, Jun 7-10.
		1993, pp 288-291.
	D237	Almedia et al. "Bond formation in ion beam synthesized amorphous gallium nitride",
		Elsevier, This Solid Films, 343-344 1999, pp 632-636.
	D238	Ascheron, C., "A Comparative Study of Swelling, Radiation, Strain and Radiation
		Damage of High-Energy Proton-bombarded GaAs, GaP, InP, SI and Ge Single
		Crystals, Nuclear Instruments and Methods in Physics Research", Nuclear
		Instruments and Methods In Physics Research B36, (1989), 163-172.
	D239	Ascheron, C., "A Study of Proton Bombardment Induced Swelling of GaP Single
		Crystals", Phys. stat. sol. (a) 92, (1985), pp 169-176.
	D240	Ascheron, C., "Gettering a Copper in Proton-and Helium-Bombarded Buried Regions
		of Gallium Phosphide", Phys. stat. sol. (a), Vol. 106, 1988, pp 73-79.
	D241	Ascheron, C., "Investigations of Hydrogen Implanted GaP Single Crystals by Means of
		Particle Induced 7-Spectroscopy, Infrared Spectroscopy, and Turyherford
		Backscattering Channeling Technique" Phys. stat. sol. (a) 89, (1985), pp 549.
	D242	Ascheron, C., "Proton Beam Modification of Selected AIIIBV Compounds", Phys. stat.
		sol. (a) 124, (1991), pp 11.
	D243	Ascheron, C., "Swelling, Strain, and Radiation Damage of He+ Implanted GaP", Phys.
		stat. sol. (a) 96, 1986, pp. 555-562. (1986).
	D244	Asheron, C., "The Effect of Hydrogen Implantation Induced Stress on GaP Single
		Crystals", Nuclear Instruments and Methods in Physics Research, B28 (1987), pp
		350-359.
	D245	Aspar et al., "The Generic Nature of the Smart-Cut© Process for Thin-Film Transfer",
		Journal of Electronic Materials, Vol. 30, No. 7, March - 2001, pp 834-840.
	D246	Aspar et al., Smart-Cut®: The basic fabrication process for UNIBOND® SOI wafers,
		SEMI 1996, pp. 37-46.
	D247	Aspar, B. "Basic Mechanisms Involved in the Smart-Cut Process", 1997, pp. 223-240.
	D248	Aspar, B. et al, "Characterization of SOI substrates: Application to Recent SIMOX and
		UNIBOND Wafers," Electrochemical Society Proceedings, vol. 96-3, pp. 99-111,
		January 1996.
	D249	Aspar, B. et al, "Transfer of Structured and Patterned Thin Silicon Films Using the
		Smart-Cut Process", 1996, pp. 1985-1986.
	D250	Aspar, B. Et al., "Ultra Thin Buried Oxide Layers Formed By Low Dose SIMOX
		Processes", Proc. 6th International Conference on SOI Technology and Devices,
		Electro. Soc., Vol. 94, No. 11, 1994, pp 62-69.

EXAMINER	DATE CONSIDERED	

		Page 8 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT	· ·	
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuon	g Nguyen et al.

EXAMINER INITIAL				
	D251	Aspar, B. et al., "Smart Cut – Process Using Metallic Bonding: Application to Transfer of Si, GaAs, InP Thin Films", Electronic Letters – June 10, 1999, Vol. 35, No. 12., pp. 1024-1025.		
	D252	Ashurst et al., "Water Level Anti-Silicon Coatings For MEMS", Sensors and Actuators A104, 2003, pp 213-221.		
	D253	Auberton-Herve, A. J. et al, "A New Sal Material: Smart-Cut", 1996, pp.214-219.		
	D254	Auberton-Herve et al., "SOI Materials for ULSI Applications", Semiconductor International, Oct. 1995, 5 pages.		
	D255	Auberton-Herve, "Why Can Smart Cut® Change The Future Of Microelectronics?" published in International Journal of High Speed Electronics and Systems, Vol. 10, No. 1 (2000) pgs. 131-146.		
	D256	Ayguavives et al., "Physical Properties of (Ba,Sr) TiO ₃ Thin Films Used for Integrated Capacitors in Microwave Applications", IEEE 2001.		
	D257	Blanchard-Lagahe C. et al., "Hydrogen and Helium Implantation to Achieve Layer Transfer" Vol. 19, pp. 346-358, 2003, Semiconductor Wafer Bonding VII: Science, Technology, and Applications – Proceedings of the International Symposium.		
		Blöchl P.E. et al., "First-Principles Calculations of Diffusion Coefficients: Hydrogen in Silicon, <i>Physical Review Letters</i> , Vol. 64, No. 12, 1990, pp 1401-1404.		
		Borgati, Stephen P., "The Root-Mean-Square", Boston College, Nov. 16, 1998, Obtained from the Internet at: http://www.analytictech.com/mb313/rootmean.htm .		
D260 Bruel, Michel, "Application of Hydrogen Ion Beams To Silicon on Insulator Mat Technology", Nuclear Instruments and Methods in Physics Research, B108, 1		Bruel, Michel, "Application of Hydrogen Ion Beams To Silicon on Insulator Material Technology", Nuclear Instruments and Methods in Physics Research, B108, 1996, pp 313-319.		
	D261	Bruel, M. et al., "Smart-Cut: A New Silicon on Insulator Material Technology Based on Hydrogen Implantation and Wafer Bonding", 1997, pp. 1636-1641, Col. 36, Part 1, No. 3B.		
	D262	Bruel, M. "Smart-Cut Process: The Way to Unibond S.O.I. Wafers", 1996, pages unknown.		
	D263	Bruel, M. et al, "Smart-Cut": A Promising New SOI material technology, <i>Proceedings</i> 1994 IEEE, International Sal Conference, Oct. 1995, pp. 178-179.		
	D264	Bruel, M. et al, "Smart-Cut-a new SOI Material Technology based on hydrogen Implantation and wafer bonding," CEA, 1996, 24 pages.		
	D265 Bruel, M., "Silicon on insulator Material Technology", Electronic Letters; 31 (1995) 6; No. 14; pp. 1201-1202.			
	D266	Bruel, M., "Silicon-an-Insulator", European Semiconductor, Mar. 1997.		
	D267 Canham et al. "Radiative Recombination Channels due to Hydrogen In Crystalline Silicon", <i>Materials Science and Engineering</i> , B4 (1989) pp. 41-45.			
	D268	Carter et al., "Applications of Ion Beams to Materials", <i>Inst. Phys. Conf. Ser.</i> , No. 28, Chapter 1, 1976, pp 30-36.		

EXAMINER	DATE CONSIDERED
and the first of a second control of the second control of	and the second of the second o

		Page 9 of 48	
FORM PTO-1449	SERIAL NO.	CASE NO.	
	10/577,175	9905/40	
		(BIF116533US)	
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT	
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813	
STATEMENT			
(use several sheets if necessary)	APPLICANT(S): Nguvet-Phuong Nguven et al.		

EXAMINER INITIAL	(Includ	OTHER ART – NON PATENT LITERATURE DOCUMENTS the name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, sisium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.
	D269	Carter, G. et al., "The Collection of lons Implanted In Semiconductors: Il Range Distributions Derived From Collection and Sputter-Etch Curves, Radiation Effects, 1972, Vol. 16, pp 107-114.
	D270	Cassidy, Victor M., "Ion Implantation Process Toughens Metalworking Tools," Modern Metals, 1984, pp. 65-67.
	D271	Cerofolini et al., "Hydrogen-Related Complexes as the Stressing Species in High- Fluence, Hydrogen-Implanted, Single-Crystal Silicon" <i>Physical Review B</i> , vol. 46, No. 4, 1992, pp. 2061-2070.
	D272	Cerofolini et al., "Hydrogen and Helium Bubbles In Silicon", <i>Material Science and Engineering 2000</i> – Reports: A Review Journal, Published By Elsevier Science S.A. 2000, pp. 1-52.
	D273	Chu et al. "Radiation Damage of 50-250 keV Hydrogen Ions in Silicon", <i>Ion Implantation in Semiconductors</i> , eds. F. Chernob et al., Plenum New York 1976, pp. 483-492.
	D274	Chu, et al. "Ion Implantation In Semiconductors", Chernow, Borders and Brice, Pirnum Press, New York and London. Radiation Damage of 50-250 keV Hydrogen Ions in Silicon, 1976, pp. 483-491.
	D275	Chu, P.K. et al., "Plasma Immersion Ion Implantation-A Fledgling Technique for Semiconductor Processing", Materials Science and Engineering Reports", A Review Journal, vol. R17, Nos. 6-7, Nov. 30, 1996, pp. 207-280.
	D276	Cowern, N. et al., "Transport Diffusion of Ion-Implanted B In Si: Dose, Time, and Matrix Dependence of Atomic and Electrical Profiles", <i>J. Appl. Phys.</i> , Vol. 68, No. 12, 1990, pp 6191-6198.
	D277	Cristoloveanu, S. et al, "Electrical Properties of Unibond Material", <i>Electrochemical Society Proceedings</i> , Vol. 96-3, pp. 142-147, 1996.
	D278	Csepregl, L. et al. "Regrowth Behavior of Ion-Implanted Amorphous Layers on <111> Silicon", Applied Physics Letters, Vol. 2, 1976, pp 92-93.
	D279	Cullis, A.G. et al. "Comparative study of annealed neon-, argon-, and krypton-ion implantation damage in silicon," <i>J. Appl. Phys.</i> , 49(10), Oct. 1978, pp. 5188-5198.
	D280	Denteneer, P. et al., "Hydrogen Diffusion and Passivation of Shallow Impurities in Crystalline Silicon, Materials Science Forum, Trans Tech Publications, Switzerland, Vols. 38-41, 1989, pp 979-984.
	D281	Denteneer, P. et al., "Structure and Properties of Hydrogen-Impurity Pairs in Elemental Semiconductors", <i>Physical Review Letters</i> , Vol. 62, No. 16, 1989, pp 1884- 1888.
	D282	Di Cioccio, L. et al., "Silicon Carbide On Insulator Formation By The Smart Cut® Process". – Materials Science and Engineering B46 (1997) – (pgs. 349-356).
	D283	DiCioccio, et al.," Silicon carbide on Insulator formation using the Smart Cut process", Electronics Letters, vol. 32, No. 12, Jun. 6, 1996, pp. 1144-1145.

EXAMINER	DATE CONSIDERED

Page 10 of 48

		Page 10 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuon	Nouven et al

EXAMINER	EYAMINER OTHER ART – NON PATENT LITERATURE DOCUMENTS				
INITIAL	(Includ	(Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.			
	D284 Diem et al., "SOI 'SIMOX': From Bulk To Surface Micromachining, A New Age For				
	Silicon Sensors and Actuators", Sensors and Actuators, Vol. A 46-47, 1995, pp				
	D285	Dirks, A. G. et al., "Columnar Microstructure In Vapor DEuropesited Thin Films", <i>Thin</i>			
	Solid Films, Vol. 47, 1977, pp 219-233.				
	D286	Donohue et al., "Pulse-Extended Excimer Laser Annealing of Lead Zirconate Titanate			
		Thin Films", Proceedings of the 12th International Symposium on Integrated			
		Ferroelectrics, Aachen, Germany, March 2000, Integrated Ferroelectics, vol. 31,			
		pages 285 to 296, 2000.			
	D287	Duo, et al., "Comparison Between The different Implantation orders in H+ and He+			
		Co-implantation", J. Phys. D. Appl. Phys. Vol. 34, 2001, pp 477-482.			
	D288	Duo, et al., "Evolution of Hydrogen and Helium Co-Implanted Single-Crystal Silicon			
		During Annealing", 2001 American Institute Physics – Journal of Applied Physics, Vol.			
		90, No. 8, October 15, 2001, pp. 3780-3786.			
	D289	Eaglesham, White, Feldman, Moriya And Jacobson, "Equilibrium Shape of Si,"			
Physical Review Letters, vol. 70, No. 11, Mar. 15, 1993, pp. 1643-1646.					
D290 EerNisse, E., "Compaction of ion-implanted fused silica", Journal of Applied F		EerNisse, E., "Compaction of ion-implanted fused silica", Journal of Applied Physics,			
	vol. 45, No.1, Jan. 1974.				
		EerNisse, E.P., "Role of Integrated Lateral Stress In Surface Deformation of He-			
	Implanted Surfaces" Journal of Applied Physics, vol. 48, No.1, Jan. 1977, pp 9-				
	D292 Evans, J.H., "An Interbubble Fracture Mechanism Of Blister Formation On Heliu				
	Irradiated Metals" Journal of Nuclear Materials, 68, 1977, pp 129-140.				
	D293 Fujitsuka et al., "A New processing Technique To Prevent Stiction Using Silicon				
	Selective Etching For SOT-MEMS", Sensors and Actruators, A97-98, 2002, pp 716				
		719.			
	D294 Garnier, D. M., "The Fabrication Of A Partial Soi Substrate", Proceedings of the 9th				
		International Symposium On Silicon On Isolator Technology and Devices, Vol. 99,			
		Chap. 54, 1990, 73-78.			
	D295	Gerasimenko, N., "Infrared Absorption of Silicon Irradiated by Protons", <i>Phys. stat.sol.</i>			
	B000	(b) 90, (1978), pp 689-695.			
	D296	Ghandi, Sorab, "VLSI Fabrication Princiles-Silicon And Gallium Arsenide", Rensselaer			
	D007	Polytechnic Institute, 1983, John Wiley & Sons publishers, pp 135.			
	D297	Goesele et al., "Semiconductor Wafer Bonding", Science and Technology, ECS			
	D298	Series, Annual Review of Material Science, Vol, 28, New Jersey, 1999, pp 215-241.			
	D298	Greenwald, A.C., "Pulsed-electron-beam annealing of ion-implantation damage", J.			
	D299	Appl. Phys. 50(2), Feb. 1978, pp. 783-786.			
	D299 D300	Grovenor, C.R.M., Microelectronic Materials, pp. 73-75 (1989).			
	D300	Guilhalmenc, C. et al, "Characterization By Atomic Force Microscopy of the SOI Layer			
		Topography in Low Dose SIMOX Materials", <i>Materials Science and Engineering</i> , B46,			
		1997, pp 29-32.			

EXAMINER	DATE CONSIDERED	

Page 11 of 48 FORM PTO-1449 SERIAL NO. CASE NO. 10/577.175 9905/40 (BIF116533US) GROUP ART UNIT LIST OF PATENTS AND PUBLICATIONS FOR FILING DATE APPLICANT'S INFORMATION DISCLOSURE April 3, 2007 2813 STATEMENT (use several sheets if necessary) APPLICANT(S): Nguyet-Phuong Nguyen et al.

EXAMINER		OTHER ART – NON PATENT LITERATURE DOCUMENTS
INITIAL	(Includ	le name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, sium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.
	D301	Haisma et al., Silicon-on-Insulator Wafer Bonding-Wafer Thinning Technological
		Evaluations", JAPANese Journal of Applied Physics, 28, 1989, Aug., No.8, Part 1,
		Tokyo, JAPAN, pp. 1426-1443.
	D302	Hamaguchi et al., "Device Layer Transfer Technique using Chemi-Mechanical
		Polishing", JAPANese Journal of Applied Physics, 23,(1984), Oct., No. 10, Part 2,
		Tokyo, JAPAN, pp. L815-L817.
	D303	Heistand et al., "Advances in Passive Integration for C/RC Arrays & Networks with
		Novel Thin & Thick Film Materials", 36th Nordic IMAPS Conference, Helsinki, 1999.
	D304	Hendrix et al., "Low-Temperature Process for High-Density Thin-Film Integrated
		Capacitors", International Conference on High-Density Interconnect and Systems
		Packaging, 2000.
	D305	Huang, et al., "Calculation of critical layer thickness considering thermal strain in Si ₁ .
		xGex/Si strained-layer heterostructures, J. Appl. Phys. 83 (1), January 1, 1998.
	D306	Hulett, D.M. et al., "Ion Nitriding and Ion Implantation: A Comparison," Metal Progress,
		1985, pp. 18-21.
	D307	IBM Technical Disclosure Bulletin, Isolation by Inert Ion Implantation, 1986, vol. 29
		No. 3, pp 1416.
	D308	IBM Technical Disclosure Bulletin, SOI Interposer Structure XP 000627972, July 1996,
		vol. 39 No. 7, pp. 1-5.
	D309	Jalaguier, E. et al., "Transfer of Thin InP Films Onto Silicon Substrate By Proton
		Implantation Process". – 11 th International Conference on Indium Phosphide and
	D040	Related Materials 16-20 May 1999 – Davos, Switzerland. (pgs. 26-27)
	D310	Jalaguier, E. et al., "Transfer of 3in GaAs Film on Silicon Substrate By Proton
	D044	Implantation Process". – (2 pgs).
	D311	Jaussaud, C. et al., 'Microstructure of Silicon Implanted With High Dose Oxygen Ions",
	D040	Appl. Phys. Lett., Vol. 48, No. 11, 1985, pp 1064-1066.
	D312	Jenei et al., "High-Q Inductors and Capacitors on Si Substrate", IEEE 2001.
	D313	Johnson, "High Fluence Deuteron Bombardment of Silicon", Radiation Effects, vol. 32, pp. 159-167, 1977.
	D314	Jones, K. S. et al., "A Systematic Analysis of Defects In Ion Implanted Silicon",
		Applied Physics A., Vol. 45, 1988 pp 1-34.
	D315	Jones et al., "Enhanced elimination of implantation damage upon exceeding the solid
		solubility", J. App. Phys., Vol. 62, No. 10, 1987, pp 4114-4117.
	D316	Kamada et al, "Observation of Blistering and Amorphization on Germanium Surface
		After 450 keV Ar+ION Bombardment, Radiation Effects, vol. 28, 1976, pp. 43-48.
	D317	Kim et al., "A Porous-Si-based Novel Isolation Technology for Mixed-Signal Integrated
		Circuits", Symposium on VLSI Technology, 2000.

EXAMINER	DATE CONSIDERED

			Page 12 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
		10/577,175	9905/40
			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE		April 3, 2007	2813
STATEMENT			
(use several sheets if necessary)	APPLICANT(S): I	Nauvet-Phuona	Nguyen et al.

EXAMINER				
INITIAL	sympo	isium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D318 Klem, J.F., "Characteristics of Lift-Off Fabricated AlGaAs/InGaAs Single-S			
		Quantum Well Structures On Glass and Silicon Substrates", Inst. Phys. Conf. Ser. No.		
		96: Chapter 6, (1989), pp. 387-392.		
	D319	Komarov et al., "Crystallographic Nature and Formation Mechanisms of Highly		
		Irregular Structure in Implanted and Annealed S1, Layers Radiation Effects, vol. 42,		
	5000	1979, pp. 169-178.		
	D320	Laporte A. et al., "Charged Defects At The Interface Between Directly Bonded Silicon		
ļ — — — — — — — — — — — — — — — — — — —	D321	Wafers" – Applied Physics, Vol. 36 (September 1997) pp. 5502-5506-Part 1, No. 9A. Li, J., "Novel Semiconductor Substrate Formed by Hydrogen Ion Implantation into		
	D32 i	Silicon," Appl. Phys. Lett., vol. 55, No. 21, Nov. 20, 1989, pp. 2223-2224.		
	D322	Ligeon, E., "Hydrogen Implantation in Silicon Between 1.5 and 60 KeV", Radiation		
		Effects 1976, vol. 27, pp. 129-137.		
	D323	Liu et al., "Investigation of Interface In Silicon-On-Insulator By Fractual Analysis",		
		Applied Surface Science, Vol. 187, Feb 28, 2002, pp 187-191.		
	D324	Liu et al., "Integrated Thin Film Capacitor Arrays", International Conference on High		
		Density Packaging and MCMs, 1999.		
		Lu, X., et al., "SOI Material Technology Using Plasma Immersion ION Implantation",		
	2000	Proceedings 1996 IEEE International SOI Conference, October 1996, pp. 48-49.		
	D326	Maleville, C. et al, "Physical Phenomena involved in the Smart-Cut Process",		
Electrochemical Society Proceeding, vol. 96-3, 1996 - pp. 34-46				
		Maleville, C. et al, "Wafer Bonding and Hi-Implantation Mechanisms Involved In The Smart-Cut Technology", 1997, pp 14-19.		
	D328	Manuaba, A., "Comparative Study on Fe32Ni36Crl4P12B 6 Metallic Glass and its		
	D320	Polycrystalline Modification bombarded by 2000 keV Helium lons with High Fluence"		
		Nuclear Instruments and Methods, (1982) pp 409-419.		
	D329	Mastrangelo, C. et al., "Suppression of Stiction in MEMS", Proceedings of the		
		Materials Research Society Seminar, Vol. 605, 2000, pp 1-12.		
	D330	Matsuda et al., "Large Diameter Ion Beam Implantation System," Nuclear Instruments		
		and Methods, vol. B21, 1987, pp. 314-316.		
	D331	Matsuo et al., "Abnormal solid solution and activation behavior in GA-implanted		
		Si(100)", Appl. Phys. Lett., Vol. 51, No. 24, 1987, pp 2037-2039.		
	D332	Mishima, Y. and T. Yagishita, T. "Investigation of the bubble formation mechanism in		
		a-Si:H films by Fourier-transform infrared microspectroscopy" J. Appl. Phys., vol. 64,		
	D333	No.8, Oct. 15, 1988, pp3972-3974.		
	Dasa	Miyagawa, S. et al, "Helium Reemission During Implantation of Silicon Carbide", <i>J. Appl. Phys.</i> , 54 (5), May 1983, pp. 2302-2306.		
	D334	Miyagawa, S., "Surface structure of silicon carbide Irradiated with helium ions with		
	D334	mono energy and continuous energy distributions" <i>J. Appl. Phys.</i> 53(12), Dec. 1982,		
		pp. 8697-8705.		

EXAMINER	DATE CONSIDERED

		Page 13 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT	·	
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuon	g Nguyen et al.

EXAMINER INITIAL			
	D335	Monemar, B. "Shallow Impurities in Semiconductors 1998", Proceedings of the Third International Conference in Sweden, Aug. 10-12, 1988, No. 95, pp 493-499.	
	D336	Moreau, Wayne M., "Semiconductor Lithography, Principles, Practices, and Materials," Plenum Press, 1988. Table of Contents only. Moriceau, H. et al, A New Characterization Process Used to Qualify SOI Films 1991 pp. 173-178.	
	D337	Moriceau, H. et al, "A New Characterization Process Used to Qualify SOI Films", Electrochemical Society Proceedings, Volume 99-3, 1999 pp. 173-178.	
	D338	Moriceau, H. et al, "A New Characterization Process Used to Qualify SOI Films", Abstract No. 405, Meeting Abstracts, The Electrochemical Society, Inc., Vol. 99-1, Seattle, May 2-6, 1999, 2 pages.	
	D339	Moriceau, H. et al. "Cleaning and Polishing As Key Steps For Smart-Cut SOI Process", Proceedings 1996 IEEE SOI Conference, Oct. 1996.	
	D340	Moriceau, H. et al, "The Smart-Cut Process as a Way to Achieve Specific Film Thickness in Sal Structures", 1997, pages unknown.	
	D341	Motohiro et al. "Geometrical Factors of Argon Incorporation In SIO ₂ Films Deposited By ION Beam Sputtering" – Thin Solid Films, Elsevier-Sequoia S.A. Lausanne, CH, Vol. 120, No. 4 – October 1, 1984 (1984-10-01), pgs. 313-327.	
	D342	Munteanu, D. et al, "Detailed Characterization of Unibond Material", 1997, pp. 395-398.	
	D343	Myers, D. R., "The effects of Ion-Implantation damage on the first order Raman spectra GaPa)" J. Appl. Phys. 54(9), Sep. 1977.	
	D344	Nethling. J. et al, "Identification of Hydrogen Platelets in ProtonBombarded GaAs", 1985, pp. 941-945.	
	D345	Nichols C. S et al., "Properties of Hydrogen in Crystalline Silicon Under Compression and Tension", <i>Physical Review Letters</i> , Vol. 63, No. 10, 1989, pp 1090-1093.	
	D346	Nicoletti, S. et al., "Bi-Epitaxial YBCO Grain Boundry Josephson Junctions on SrTiO3 and Sapphire Substrates", <i>Physics C269</i> , 1996, pp 255-267.	
	D347	Ono et al., "Orientation Dependence of Flaking of Ion Irradiated Aluminum Single Crystals", <i>Japanese Journal of Applied Physics</i> , vol. 25, No., 10, 1986, pp. 1475-1480.	
	D348	Paszti, E, "Flaking and Wave-Like Structure on Metallic Glasses Induced by MeV- Energy Helium Ions", <i>Nuclear Instruments and Methods</i> , Vol. 209/210, (1983), pp. 273-280.	
	D349	Picraux, S. Thomas et al., "Ion Implantation of Surfaces," <i>Scientific American</i> , vol. 252, No.3, pp. 102-113 1985.	
	D350	Popov, V.P. et al., "Blistering On A Silicon Surface in the Process of Sequential Hydrogen/Hellium ION Co-Iplantation" - Optoelectionics Instrumentation and Data Processing, No. 3, April 5, 2001 - pp. 90-98 – 2001.	
	D351	Primak, W., "Impurity Effect in the Ionization Dilation of Vitreous Silica" <i>J. Appl. Phys.</i> 39(13) 1968.	

EXAMINER	DATE CONSIDERED

Page 14 of 48

			Page 14 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
		10/577,175	9905/40
			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE		April 3, 2007	2813
STATEMENT			
(use several sheets if necessary)	APPLICANT(S): N	lauvet-Phuona	Nguven et al.

EVAMINED	OTHER ART – NON PATENT LITERATURE DOCUMENTS				
EXAMINER INITIAL	(Includ	le name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, sium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.			
	D352	Ray et al. "Effect of Reactive-Ion Bombardment on the Properties of Silicon Nitride and Oxynitride Films Deposited By Ion-Beam Sputtering" – Journal of Applied Physics, Vol. 75, No. 12, June 15, 1994 – pas. 8145-8152.			
	D353	Renier, M. et al., "A New Low-Energy Ion Implanter for Bombardment of Cylindrical Surfaces," Vacuum, vol. 35, No. 12, pp. 577-578, 1985.			
	D354	Roozeboom et al., "High-Value MOS Capacitor Arrays in Ultradeep Trenches in Silicon", <i>Microelectronic Engineering</i> , vol. 53, pages 581 to 584, Elsevier Science 2000.			
	D355	Roth, J., "Blistering and Bubble Formation" <i>Inst. Phys. Conf.</i> Ser. No. 28, 1976: Chapter 7, pp 280-293.			
	D356	Sah, Chih -Tang et al., "Deactivation of the Boron Acceptor in Silicon by Hydrogen," Appl. Phys. Lett. 43, (2), Jul. 1983, pp. 204-206			
	D357	Saint-Jacques R. G., "La Formation des Cloques", Nuclear Instruments and Methods, No. 209/210", North Holland Publishing Co., 1983, pp 333-343.			
	D358	Schnell et al., "Plasma Surface Texturization for Multicrystaline Silicon Solar Cells", IEEE, XXVIII, Photovoltaic Conference, 2000, pp 367-370.			
	D359	Shintani, A. et al., "Temperature dependence of stresses in chemical deposited vitreous films", <i>J. Appl. Phys.</i> , Vol. 51, No. 8, 1980, pp 4197.			
	D360	Silicon-On-Insulator, European Semiconductor, Mar. 1997, pp. 17-18.			
	D361	Sioshansi, Piran, "Ion Beam Modification of Materials for Industry," <i>Thin Solid Film</i> , vol. 118, 1984, pp. 61-71.			
	D362	Snyman, H. C., "Transmission Electron Microscopy of Extended Crystal Defects in Proton Bombarded and Annealed GaAs", <i>Radiation Effects</i> , 1983, vol. 69, pp. 199–230.			
	D363	Snyman, H. C. et al, "Void Formation in Annealed Proton-Bombarded GaAs", 1981, pp. 243-245.			
	D364	Stein, Myers and Follstaedt, "Infrared Spectroscopy of chemically bonded hydrogen at voids and defects in silicon", <i>J. Appl. Phys.</i> 73(b6), Mar. 15, 1993, pp. 2755-2764.			
	D365	Stephen, D., "Investigation of Lattice Strain in Proton-Irradiated GaP by a Modified Auleytner Technique" <i>Phys. stat. sol.</i> (a) 87, 1985, pp. 589- 596.			
	D366	Sunkara et al., "Bulk synthesis of silicon nanowires using a low-temperature vapor- liquid-soild solution", <i>Applied Physics Letters</i> , Vol. 79, No. 10, September 3, 2001, pp 1546-1548.			
	D367	Sze, S.M., VLSI Technology, 2.sup.nd Ed., 1988, pp. 9-10.			
	D368	Tan, T. Y. et al., "On Oxygen Precipitation Retardation/Recovery Phenomena, Nucleation Incubation Phenomena and The Exigent-Accomodation-Volume Factor of Precipitation", Proceedings of the 5 th International Symposium On Silicon Materials Science and Technology, Semiconductor Silicon 198 Electrochem. Soc., New Jersey, 1986, pp 864-873.			

EXAMINER	DATE CONSIDERED

Page 15 of 48

			Page 15 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
		10/577,175	9905/40
			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE		April 3, 2007	2813
STATEMENT			
(use several sheets if necessary)	APPLICANT(S): I	Nauvet-Phuona	Nouven et al.

EXAMINER				
INITIAL	sympo	le name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, sium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D369	Terada, K. et al., "A New Dram Cell With A Transistor On A Lateral Epitaxial Silicon		
		Layer (Tole Cell)", IEEE Transactions On Electron Device, Vol. 37, No. 9, 1990, pp		
		2052-2057.		
	D370	Theodore, N. David et al., "TFSOI With Improved Oxidation Resistance (To Reduce		
		Isolation Induced Stresses and Leakage), Motorola Bulletin XP 000691920, Technical		
		Developments, Nov. 1996, pp 158-59.		
	D371	Tillman et al., "Zero-Level Packaging for MEMS or MST Devices: The IRS Method",		
		MEMS/Sensors, Advancing Microelectronics, Pages 37-39, November/December		
	D372	2000.		
	D372	Tomisaka et al., "Electroplating Cu Fillings for Through-Vias for Three-Dimensional Chip Stacking" (Electronic Components and Technology Conference, 2002).		
	D373	Tonini, Monelli, Cornl, Ottaviani, Frabboni, Canteri, Queirolo, "Hydrogen Interaction		
	D3/3	with phosphorus ion implantated silicon". <i>Ion Implantation Technology</i> -94, (1995) pp.		
		801-804.		
	D374	Tzeng, J.C., "A Novel Self-Aligned Oxgyen (Salox) Implanted SOI Mosfet Device		
		Structure" Nuclear Instruments and Methods in Physics Research B2, 1987, pp. 112-		
		115.		
and Basic Science Resulting Fror Energy Program", Plasma Coatin		U.S. Dept. of Energy, "The Fusion Connection: Contributions to Industry, Defense,		
		and Basic Science Resulting From Scientific Advances Made in the Magnetic Fusion		
		Energy Program", Plasma Coating, pp. 6-7, 1985.		
	D376	Van de Walle, C. "Structural Identification of Hydrogen and Muonium Centers in		
		Silicon First Principles Calculations of Hyperfine Parameters", Physical Review		
	D377	Letters, Vol. 60, No. 26, 1988, pp 2761-2764.		
	D377	Van de Walle, C. "Theoretical Aspects of Hydrogen in Crystalline Semiconductors", Physica B, Holland, Vol. 170, No. 15, 1991, pp 21-32.		
	D378	Van de Walle, C. "Theory of Hydrogen Diffusion and Reactions in Crystalline Silicon",		
	D376	Physical Review Letters, Vol. 64, No. 6, 1980, pp 669-672.		
	D379	Van de Walle, C. "Theory of Hydrogen Diffusion and Reactions in Crystalline Silicon".		
		Physical Review B, Vol. 39, No. 15, 1989, pp 10 791-10 808, plus diagrams.		
	D380	Van Swijgenhoven et al. "Helium Bubble and Blister Formation for Nickel and An		
		AMorphous Fe-Ni-Mo-B Alloy During 5 kev He-+-Irradiation at Temperatures Between		
		200 K and 600", Nuclear Instruments and Methods, 209/210, 1983, pp. 461-468.		
	D381	Veldkamp, W.B. et al., "Binary Optics," Scientific American, 1992, pp. 50-55.		
	D382	Venezia et al., "The Role of Implantation Damage in the Production of Silicon-On-		
		Insulator Films By Co-Implantation Of He ⁺ and H ⁺ ", Electrochemical Society		
		Proceedings Volume 98-1, 1998 - pp. 1384-1395.		
	D383	Weldon et al., "Mechanism Of Silicon Exfoliation Induced by Hydrogen/Hekium Co-		
		implantation", Applied Physics Letters, Vol. 73, No. 25, pp 3721-3723, Dec 21, 1998.		

EXAMINER	DATE CONSIDERED	

			Page 16 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
		10/577,175	9905/40
			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE		April 3, 2007	2813
STATEMENT			
(use several sheets if necessary)	APPLICANT(S):	Nauvet-Phuona	Nguyen et al.

EXAMINER INITIAL	(Includ	OTHER ART – NON PATENT LITERATURE DOCUMENTS te name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, sium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.
	D384	Wemple, S.H., "Optical and channeling studies of ion-bombarded GaP", <i>J. Appl. Phys.</i> , vol. 45, No.4, Apr. 1974, pp 1578-1588.
	D385	Whitton, J. L. et al., "The Collection of Ions Implanted In Semiconductors: 1 Saturations Effects", Radiation Effects, Scotland, Vol. 16, 1972, pp 101-105.
	D386	Wiegand, M. et al., "Wafer Bonding of Silicon Wafers Covered With Various Surface Layers", Sensors and Actuators, Elsevier Science B.V., Vol. 86, 2000, pp 91-95.
	D387	Williams J. et al., "Annealing behaviour of high-dose rare-gas implantations into silicon", from Application of Ion Beans to Materials, 1975, Chap. 1, Inst. Phys. Conf. Ser. No. 28, 1976, pp 30-36.
	D388	Wittmaack et al., "High Fluence Retention of Noble Gases Implanted in Silicon" Radiation Effects, vol. 39, 1978, pp. 81-95.
	D389	Wolf, Stanley Ph.D., Silicon Processing for the VLSI Era (vol. 2), Lattice Press, 1990, pp. 66-79.
	D390	Yamaguchi H. et al., "Intelligent Power IC With Partial Soi Structure", Jpn. J. Appl. Phys., Vol. 34, 1995, pp 864-868.
	D391	Yee et al., "Polysilicon Surface-Modification Technique to Reduce Sticking of Microstructures", Sensors and Actuators A 52, 1996, pp. 145-150.
	D392	Yun, H. et al., "Transfer of Patterned Ion-Cut Silicon Layers", Applied Physics Letters Vol. 73, No. 19, 1998, pp 2772-2774.
	D393	International Search Report for International Application No. PCT/FR1998/002904, dated April 16, 1999, 2 pages.
	D394	International Search Report for International Application No. PCT/FR2002/003422, dated January 22, 2003, 3 pages.
	D395	International Search Report for International Application No. PCT/FR2003/003256, dated March 19, 2004, 6 pages.
	D396	International Search Report for International Application No. PCT/FR2003/003867, dated May 28, 2004, 3 pages.
	D397	International Search Report for International Application No. PCT/FR2003/003622, dated June 3, 2004, 3 pages.
	D398	International Search Report for International Application No. PCT/FR2004/001858, dated December 28, 2004, 3 pages.
	D399	International Search Report for International Application No. PCT/FR2004/002779, dated April 5, 2005, 3 pages.
	D400	International Search Report for International Application No. PCT/FR2004/002781, dated April 5, 2005, 3 pages.
	D401	International Search Report for International Application No. PCT/FR2004/001565, dated July 6, 2005, 3 pages.
	D402	International Search Report for International Application No. PCT/FR2006/002184, dated January 24, 2007, 2 pages.

ı	EXAMINER	DATE CONSIDERED
ı		
1		

pages.

pages.

pages.

pages.

pages.

D426

D429

EXAMINER

					Page 17 of 48
FORM PTO-1449			SERIAL NO.		CASE NO.
				10/577,175	9905/40
					(BIF116533US)
		NTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLI	CANT'S	INFORMATION DISCLOSURE		April 3, 2007	2813
,		STATEMENT	1 mm 10 11 mm (0)		
(use several s	sheets if	necessary)	APPLICANT(S):	Nguyet-Phuong	Nguyen et al.
	_	OTHER ART – NON PA	TENT LITEDATI	DE DOCUMEN	те
EXAMINER	(Includ	OTHER ART - NON PA			
INITIAL	sympo	sium, catalog, etc.), date page(s), volume-issu	e number(s), publish	er, city and/or cou	ntry where published.
	D403	International Search Report for International	ernational Applic	ation No. PCT/	FR2007/000534,
		dated November 22, 2007, 3 pages	S.		
	D404	International Search Report for Inte	ernational Applic	ation No. PCT	FR2007/002100,
dated February 4, 2009, 3 pages.					
		ernational Application No. PCT/FR2008/001427,			
D406 Office Action from US Application No. 12/063,808, da			dated April 6, 2	ed April 6, 2010, 9 pages.	
D407 Office Action from US Application No. 12/063,808, dated September 22, 2010,		per 22, 2010, 9			
		pages.		·	
	D408	Office Action from US Application I	No. 10/534,199,	dated Februar	/ 19, 2009, 8 pages.
	D409	Office Action from US Application I			
	D410	Office Action from US Application I	No. 10/534,199.	dated January	20, 2010, 8 pages.
	D411	Office Action from US Application I			
	D412	Office Action from US Application I			
	D413	Office Action from US Application I			
		pages.			,,
	D414	Office Action from US Application I	No. 11/480.250.	dated January	26, 2010, 14 pages.
	D415	Office Action from US Application			
	D416	Office Action from US Application I			
		Tomos ristion ironi do Application i	10. 12/000,047,	dated Septemi	JOI 20, 2000, 0

D417 Office Action from US Application No. 12/088,047, dated March 10, 2010, 9 pages. D418 Office Action from US Application No. 10/561,299, dated March 26, 2008, 9 pages. D419 Office Action from US Application No. 10/561,299, dated December 9, 2008, 11 D420 Office Action from US Application No. 10/561,299, dated May 11, 2009, 12 pages. D421 Office Action from US Application No. 10/561,299, dated November 16, 2009, 11

D422 Office Action from US Application No. 10/561,299, dated November 27, 2009, 10

D423 Office Action from US Application No. 10/561,299, dated May 11, 2010, 11 pages. D424 Office Action from US Application No. 10/565,621, dated May 15, 2007, 13 pages. D425 Office Action from US Application No. 10/565,621, dated February 11, 2008, 11

Office Action from US Application No. 10/565.621, dated September 12, 2008, 9 D427 Office Action from US Application No. 10/565,621, dated March 12, 2009, 6 pages. D428 Office Action from US Application No. 10/565,621, dated January 7, 2010, 8 pages.

Office Action from US Application No. 10/565.621, dated November 23, 2010, 11

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609: Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

DATE CONSIDERED

		Page 18 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuon	Nouven et al

EXAMINER		OTHER ART – NON PATENT LITERATURE DOCUMENTS
INITIAL	(Includ	le name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, sium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.
	D430	Office Action from US Application No. 12/628,772, dated October 7, 2010, 12 pages.
	D431	Notice of Allowance from US Application No. 12/336,229, dated September 29, 2010,
		7 pages.
	D432	Notice of Allowance from US Application No. 12/336,229, dated January 10, 2011, 4
		pages.
	D433	Office Action from US Application No. 10/468,223, dated October 5, 2005, 7 pages.
	D434	Office Action from US Application No. 10/468,223, dated May 3, 2006, 11 pages.
	D435	Office Action from US Application No. 10/468,223, dated January 10, 2007, 11 pages.
	D436	Office Action from US Application No. 10/468,223, dated July 20, 2007, 11 pages.
	D437	Office Action from US Application No. 10/468,223, dated February 11, 2008, 11
		pages.
	D438	Office Action from US Application No. 10/468,223, dated October 29, 2008, 11 pages.
	D439	Office Action from US Application No. 10/468,223, dated June 25, 2009, 8 pages.
	D440	Notice of Allowance from US Application No. 10/468,223, dated December 28, 2009,
		pages.
	D441	Office Action from US Application No. 10/474,984, dated September 24, 2004, 6
		pages.
	D442	Office Action from US Application No. 10/474,984, dated June 6, 2005, 5 pages.
	D443	Office Action from US Application No. 10/474,984, dated November 16, 2005, 5
		pages.
	D444	Office Action from US Application No. 10/474,984, dated May 17, 2006, 5 pages.
	D445	Office Action from US Application No. 10/474,984, dated May 7, 2007, 9 pages.
	D446	Office Action from US Application No. 10/474,984, dated February 6, 2008, 10 pages.
	D447	Office Action from US Application No. 10/474,984, dated October 17, 2008, 11 pages
	D448	Office Action from US Application No. 10/474,984, dated July 7, 2009, 10 pages.
	D449	Office Action from US Application No. 10/474,984, dated March 11, 2010, 13 pages.
	D450	Notice of Allowance from US Application No. 10/474,984, dated October 28, 2010, 6
		pages.
	D451	Office Action from US Application No. 10/540,303, dated December 18, 2007, 6
		pages.
	D452	Notice of Allowance from US Application No. 10/540,303, dated October 7, 2008, 9
		pages.
	D453	Office Action from US Application No. 11/327,906, dated October 1, 2007, 5 pages.
	D454	Office Action from US Application No. 11/327,906, dated February 11, 2008, 5 pages.
	D455	Notice of Allowance from US Application No. 11/327,906, dated September 15, 2008,
		6 pages.
	D456	Office Action from US Application No. 10/975,826, dated September 2, 2009, 24
		pages.

EXAMINER	DATE CONSIDERED

		Page 19 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuor	n Nouven et al

EXAMINER INITIAL			
INITIAL			
	D457	Notice of Allowance from US Application No. 10/975,826, dated April 28, 2010, 8 pages.	
	D458	Office Action from US Application No. 10/492,343, dated October 17, 2005, 6 pages.	
	D459	Office Action from US Application No. 10/492,343, dated June 6, 2006, 13 pages.	
	D460	Office Action from US Application No. 10/492,343, dated November 14, 2006, 13 pages.	
	D461	Office Action from US Application No. 10/492,343, dated May 29, 2007, 15 pages.	
	D462	Office Action from US Application No. 10/492,343, dated February 7, 2008, 18 pages.	
	D463	Office Action from US Application No. 10/492,343, dated August 18, 2008, 12 pages.	
	D464	Office Action from US Application No. 10/492,343, dated December 22, 2008, 9 pages.	
	D465	Notice of Allowance from US Application No. 10/492,343, dated June 26, 2009, 6 pages.	
	D466	Office Action from US Application No. 11/747,733, dated March 16, 2009, 9 pages.	
	D467	Office Action from US Application No. 11/747,733, dated March 23, 2010, 5 pages.	
	D468	Notice of Allowance from US Application No. 11/747,733, dated September 29, 2010, 8 pages.	
	D469	Notice of Allowance from US Application No. 12/293,193, dated October 8, 2009, 10 pages.	
	D470	Expert Report of Marcus Weldon, Ph.D. dated November 1, 2000	
	D471	Expert Report of Jean-Pierre Colinge dated November 1, 2000.	
	D472	Expert Report of Chris Van de Walle, Ph.D. dated November 1, 2000	
	D473	Memorandum in Support of Defendant Silicon Genesis Corporation's Motion for Summary Judgment of Invalidity for Lack of Enablement dated March 19, 2001	
	D474	Memorandum of Points and Authorities In Support of Soitec's Motion for Summary Judgment on Sigen's Enablement Invalidity Claim (Redacted) dated March 27, 2001	
	D475	Soitec's Memorandum of Points and Authorities In Opposition to Silicon Genesis Corporation's Motion for Summary Judgment of Invalidity for Lack of Enablement dated April 11, 2001	
	D476	Memorandum in Support of Defendant Silicon Genesis Corporation's Opposition to Soitec's Motion for Summary Judgment on SiGen's Defense of Enablement dated April 20, 2001	
	D477	Reply Memorandum in Support of Defendant Silicon Genesis Corporation's Motion for Summary Judgment of Invalidity for Lack of Enablement dated April 30, 2001	
	D478	Expert Report of Marcus Weldon, Ph.D. dated August 24, 2001	
	D479	Report of Jean-Pierre Colinge in Response to SiGen Enablement and Indefiniteness Expert Reports of August 24, 2001	

EXAMINER	DATE CONSIDERED

Page 20 of 48

		Page 20 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuon	n Nouven et al.

EXAMINER	OTHER ART – NON PATENT LITERATURE DOCUMENTS		
INITIAL	sympo	le name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, ssium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.	
	D480 Expert Report of Chris Van de Walle, Ph.D. dated August 24, 2001		
	D481	Memorandum and Order re: Summary Judgment [denied] dated February 5, 2002	
	D482	Plaintiff's Memorandum in Support of Their Motion for Judgment As a Matter of Law	
	and a New Trial dated May 10, 2002		
	D483 Silicon Genesis Corporation's Opposition to Plaintiff's Motion for Judgment as		
		of Law and a New Trial dated June 17, 2002	
	D484	Memorandum of Law in Support of Plaintiff's Motion for Judgment on SiGen's	
		Indefiniteness Defense dated June 20, 2002	
	D485	Plaintiff's Reply Memorandum in Support of Their Motion for Judgment as a Matter of Law and a New Trial dated July 18, 2002	
	D486	Defendant Silicon Genesis Corporation's Opposition to Soitec's Motion for Judgment Re Indefiniteness and Cross-Motion for Judgment of Indefiniteness dated July 19, 2002	
	D487 Plaintiff's Reply in Support of their Motion for Judgment on SiGen's Indefiniten Defense dated July 25, 2002		
D488 Memorandum and Order re: Post-Trial Motions dated August 23, 2002		Memorandum and Order re: Post-Trial Motions dated August 23, 2002	
D489 Judgment dated October 21, 2002.		Judgment dated October 21, 2002.	
		Brief of Plaintiffs-Appellants Soitec, S.A. and Commissariat a L'Energie Atomique dated January 28, 2003	
	D491 Brief for Defendant-Cross Appellant Silicon Genesis Corporation dated Marc 2003		
	D492	Reply Brief of Plaintiffs-Appellants Soltec, S.A. and Commissariat a L'Energie Atomique dated May 5, 2003	
	D493	Reply Brief for Defendant-Cross Appellant Silicon Genesis Corporation dated May 19, 2003	
	D494	Plaintiff/Appellants Supplemental Authority Letter [dated November 17, 2003].	
	D495 Defendant-Cross Appellant's Response To Appellants' Submission Of CFMT, Inc. v. Yieldup Int'l, [dated November 24, 2003].		
	D496 Decision from the United States Court of Appeals for the Federal Circuit dated November 26, 2003.		
	D497	Combined Petition for Panel Rehearing and for Rehearing En Banc by Plaintiffs- Appellant's Soitec, S.A. and Commissariat A L'Energie Atomique, dated December 10, 2003.	
	D498	Order [dated January 7, 2004 denying Appellants' petition for panel rehearing and Appellant's petition for rehearing en banc].	
	D499	Judgment Mandate [dated January 14, 2004].	

EXAMINER	DATE CONSIDERED	

Page 21 of 48

			Page 21 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
		10/577,175	9905/40
			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE		April 3, 2007	2813
STATEMENT			
(use several sheets if necessary)	APPLICANT(S):	Nauvet-Phuona	Nguyen et al.

(use several s	use several sheets if necessary) Art Licant (0). Nguyet-muong nguyen et al.				
EXAMINER INITIAL					
	D500	NOTICE of by SOITEC Silicon On Insulator Technologies SA, Commissariat a L'Energie Atomique re 30 MOTION to Dismiss Based upon Fed. R. Civ. P. 12(b)(1) and (6) and Article III of the United States Constitution MOTION to Dismiss Based upon Fed. R. Civ. P. 12(b)(1) and (6) and Article III of the United States Constitution Notice of Withdrawal of Plaintiffs' Partial Motion to Dismiss Counterclaim Counts II, III, IV, V, and VIII (Attachments: #1 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2009)			
	D501	STIPULATION and [Proposed] Order to File an Amended Complaint by SOITEC Silicon On Insulator Technologies SA, Commissariat a LEnergie Atomique. (Attachments: #1 Exhibit A, #2 Certificate of Service)(Kraft, Denise) (Entered: 07/16/2009)			
	D502	NOTICE OF SERVICE of Soitec's Objections and Responses to MEMC's Second Request For Production of Documents and Things Directed To Soite or <u>46</u> Notice of Service by SOITEC Silicon On Insulator Technologies SA, Commissariat a LEnergie Atomique. Related document: <u>46</u> Notice of Service filed by MEMC Electronic Materials Inc. (Attachments: # <u>1</u> Certificate of Service)(Kraft, Denise) (Entered: 07/16/2009)			
	D503	First AMENDED COMPLAINT for Patent Infringement against MEMC Electronic Materials Incfiled by SOITEC Silicon On Insulator Technologies SA, Commissariat a L'Energie Atomique. (Attachments: # 1 Exhibit Exhibit 1, # 2 Exhibit Exhibit 2, # 3 Exhibit Exhibit 3, # 4 Exhibit Exhibit 4, # 5 Certificate of Service)(Kraft, Denise) (Entered: 07/21/2009)			
	D504	ANSWER to Amended Complaint ANSWER to 57 Amended Complaint, with Under Federal Rule of Civil Procedure 38, MEMC demands a trial by jury on all issues so triable, COUNTERCLAIM against all plaintiffs by MEMC Electronic Materials Inc (Attachments: # 1 Exhibit A, # 2 Certificate of Service)(Rogowski, Patricia) (Entered: 08/03/2009)			
	D505	ANSWER to 60 Answer to Amended Complaint, Counterclaim,,, COUNTERCLAIM Reply to Defendant's Amended Counterclaims, Counterclaims And Affirmative Defenses against MEMC Electronic Materials Inc. by SOITEC Silicon On Insulator Technologies SA, Commissariat a L'Energie Atomique, SOITEC U.S.A., Inc (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 08/31/2009)			
	D506	NOTICE OF SERVICE of MEMC'S THIRD SET OF INTERROGATORIES DIRECTED TO S.O.I.TEC SILICON ON INSULATOR TECHNOLOGIES, S.A., SOITEC USA, INC., AND COMMISSARIAT A L'ENERGIE ATOMIQUE by MEMC Electronic Materials Inc. (Rogowski, Patricia) (Entered: 09/01/2009)			

EXAMINER	DATE CONSIDERED

Page 22 of 48

		Page 22 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT	·	
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuono	Nouven et al.

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D507	ANSWER to 68 Answer to Counterclaim,, by MEMC Electronic Materials Inc(Rogowski, Patrica) (Entered: 09/14/2009). Minute Entry for proceedings held before Judge Sue L. Robinson - Discovery Conference held on 9/16/2009. (Court Reporter V. Gunning.) (nmf) (Entered: 09/16/2009)	
	D508	MOTION to Bifurcate the Issues of Willfulness and Damages for Purposes of Discovery and Trial and proposed Form of Order - filed by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 10/20/2009).	
		CORRECTING ENTRY: Docket clerk deleted D.I. 78 (opening brief) due to document being filed improperly. Counsel is advised to re-file document using the OPENING BRIEF event code rather than the combined opening and answering brief event code. (lid) (Entered: 10/21/2009)	
	D509	OPENING BRIEF in Support re <u>77</u> MOTION to Bifurcate the Issues of Willfulness and Damages for Purposes of Discovery and Trial and proposed Form of Order filed by MEMC Electronic Materials IncAnswering Brief/Response due date per Local Rules is 11/9/2009. (Attachments: # 1 Exhibit A, # 2 Exhibit B, # 3 Exhibit C)(Rogowski, Patricia) (Entered: 10/21/2009)	
	D510	Cross MOTION to Bifurcate all Collateral Issues - filed by SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc., Commissariat a LEnergie Atomique. (Attachments: # 1 Text of Proposed Order, # 2 Certificate of Service)(Kraft, Denise) (Entered: 11/09/2009)	
	D511	ANSWERING BRIEF in Opposition re 85 Cross MOTION to Bifurcate all Collateral Issues, 77 MOTION to Bifurcate the Issues of Willfulness and Damages for Purposes of Discovery and Trial and proposed Form of Order filed by SOITEC Silicon On Insulator Technologies SA, Commissariat a LEnergie Atomique. Reply Brief due date per Local Rules is 11/20/2009. (Attachments: # 1 Exhibit, # 2 Exhibit, # 3 Exhibit, # 4 Exhibit, # 5 Exhibit, # 6 Exhibit, # 10 Exhibit, # 11 Exhibit, # 12 Declaration, # 13 Certificate of Service)(Kraft, Denise) (Entered: 11/09/2009)	
	D512	REPLY BRIEF re 77 MOTION to Bifurcate the Issues of Willfulness and Damages for Purposes of Discovery and Trial and proposed Form of Order filed by MEMC Electronic Materials Inc. (Attachments: # 1 Exhibit 1, # 2 Exhibit 2, # 3 Exhibit 3)(Rogowski, Patricia) (Entered: 11/17/2009)	
	D513	ANSWERING BRIEF in Opposition re <u>85</u> Cross MOTION to Bifurcate all Collateral Issues filed by MEMC Electronic Materials IncReply Brief due date per Local Rules is 12/3/2009. (Rogowski, Patricia) (Entered: 11/19/2009)	

EXAMINER	DATE CONSIDERED

Page 23 of 48

		Page 23 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuone	Nouven et al.

EXAMINER INITIAL	(Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D514	REPLY BRIEF re \$5 Cross MOTION to Bifurcate all Collateral Issues filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Exhibit Declaration of Marcus T. Hall in Support of Plaintiffs' Reply Re: Cross-Motion to Bifurcate all Collateral Issues)(Kraft, Denise) (Entered: 12/03/2009)	
	D515	NOTICE OF SERVICE of S.O.I.TEC Silicon On Insulator Technologies, S.A. and Commissariat a L'Energie Atomique's Production of Three Boxes of Wafer Samples by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1_Certificate of Service)(Kraft, Denise) (Entered: 12/08/2009). Set Hearings: Discovery Conference set for 12/21/2009 04/00 PM in Courtroom 6B before Judge Sue L. Robinson. (nmf) (Entered: 12/09/2009).	
	D516	MOTION for Leave to File Stipulated Motion for Leave to File a Sur-Reply Brief in Support of MEMC's Motion to Bifurcate - filed by MEMC Electronic Materials Inc (Attachments: # 1 Exhibit 1)(Rogowski, Patricia) (Entered: 12/14/2009)	
	D517	SUR-REPLY BRIEF re 77 MOTION to Bifurcate the Issues of Willfulness and Damages for Purposes of Discovery and Trial and proposed Form of Order MEMC's SUR-REPLY BRIEF IN SUPPORT OF ITS MOTION TO BIFURCATE THE ISSUES OF WILLFULNESS AND DAMAGES FOR PURPOSES OF DISCOVERY AND TRIAL filed by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 12/16/2009)	
	D518	MOTION for Discovery MOTION FOR THE ADMISSION OF THE EXPERT TESTIMONY OF JOHN T. GOOLKASIAN RELATING TO THE CERTIFICATE OF CORRECTION FOR U.S. PATENT NO. 7,067,396 - filed by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 05/07/2010)	
	D519	OPENING BRIEF in Support re 141 MOTION for Discovery MOTION FOR THE ADMISSION OF THE EXPERT TESTIMONY OF JOHN T. GOOLKASIAN RELATING TO THE CERTIFICATE OF CORRECTION FOR U.S. PATENT NO. 7,067,396 filed by MEMC Electronic Materials Inc. Answering Brief/Response due date per Local Rules is 5/24/2010. (Attachments: #1 Exhibit 1, #2 Exhibit 2, #3 Exhibit 3, #4 Exhibit 4, #5 Exhibit 6, #7 Exhibit 7, #8 Exhibit 8, #9 Exhibit 9, #10 Exhibit 10, #11 Exhibit 11, #12 Exhibit 12, #13 Exhibit 13, #14 Exhibit 14, #15 Exhibit 10, #15 [Stripped Solve 15] [Post 15] [Post 15] [Post 16]	

EXAMINER	DATE CONSIDERED

EXAMINER

Page 24 of 48

					Page 24 of 48
FORM PTO-1	449		SERIAL NO.	10/577,175	CASE NO. 9905/40
LIST OF PATENTS AND PUBLICATIONS FOR			FILING DATE		(BIF116533US) GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE STATEMENT			FILING DATE	April 3, 2007	2813
(use several s	heets it	f necessary)	APPLICANT(S):	: Nguyet-Phuong	Nguyen et al.
		OTHER ART. NON RA	TENT LITEDATI	DE DOCUMEN	TO
EXAMINER INITIAL OTHER ART – NON PATENT LITERATURE DOCUMENT (Include name of author, title of the article (when appropriate), title of the item (book, magazin symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or count					ine, journal, serial.
	D520	ANSWERING BRIEF in Opposition ADMISSION OF THE EXPERT TE TO THE CERTIFICATE OF CORR Plaintiff's Answering Brief in Oppos Expert Testimony of John T. Goolk Technologies SA.Reply Brief due c Certificate of Service)(Kraft, Denise	STIMONY OF J ECTION FOR U ition to Defenda asian filed by So late per Local Ri	OHN T. GOOL J.S. PATENT N Int's Motion Fo OITEC Silicon Jules is 6/4/201	KASIAN RELATING IO. 7,067,396 r the Admission of On Insulator
	D521	DECLARATION re 145 Answering in Support of Plaintiff's Answering In Admission of Expert Testimony of Technologies SA. (Attachments: # D, # 5 Exhibit E, # 6 Exhibit F, # 7 # 11 Exhibit K, # 12 Exhibit L, # 13 Service)(Kraft, Denise) (Entered: O	Brief in Opposition John T. Goolkas Exhibit A, # 2 Exhibit G, # 8 Exhibit M, # 14	on to Defendar ian by SOITEC Exhibit B, # 3 I khibit H, # 9 Ex	nt's Motion For the C Silicon On Insulator Exhibit C, # 4 Exhibit Thibit I, # 10 Exhibit J,
	D522	REPLY BRIEF IN SUPPORT OF 1 ADMISSION OF THE EXPERT TE TO THE CERTIFICATE OF CORR MEMC Electronic Materials Inc (A 3, #4 Exhibit 4, #5 Exhibit 5, #6 E (lid). (Entered: 06/04/2010)	STIMONY OF J ECTION FOR U ttachments: # 1	OHN T. ĞOOL J.S. PATENT N Exhibit 1, # <u>2</u> I	KASIAN RELATING IO. 7,067,396 filed by Exhibit 2, # <u>3</u> Exhibit
	D523	STATEMENT re 148 Stipulation Jo a LEnergie Atomique, SOITEC Sili- Inc (Attachments: # 1 Certificate of	con On Insulator	r Technologies	SA, SOITEC U.S.A.,
	D524	CLAIM Construction Chart by Com Insulator Technologies SA, SOITE Service)(Kraft, Denise) (Entered: 0	C U.S.A., Inc (/		
	D525	SUR-REPLY BRIEF re 141 MOTIC OF THE EXPERT TESTIMONY OI CERTIFICATE OF CORRECTION Plaintiffs to Motion by Defendant F Goolkasian filed by SOITEC Silicor Certificate of Service)(Kraft, Denise	F JOHN T. GOO FOR U.S. PATE or The Admission On Insulator To	LKASIAN REL ENT NO. 7,067 on of Expert Te echnologies SA	ATING TO THE ,396 Surreply by stimony of John T.
	D526	DECLARATION re 157 Sur-Reply Surreply by Plaintiffs to Motion by I of John T. Goolkasian by SOITEC (Attachments: # 1 Exhibit A, # 2 Ex of Service)(Kraft, Denise) (Entered	Defendant For T Silicon On Insula hibit B, #3 Exhi	he Admission of ator Technolog	of Expert Testimony ies SA.

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

DATE CONSIDERED

Page 25 of 48

			Page 25 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
		10/577,175	9905/40
A			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE		April 3, 2007	2813
STATEMENT			
(use several sheets if necessary)	APPLICANT(S):	Nguyet-Phuong	Nguyen et al.

(use several s	sneets it	necessary) APPLICANT(S): Nguyet-Phuong Nguyen et al.	
EXAMINER INITIAL			
		Attachments: # 1 Appendix DA0001-DA0006, # 2 Áppendix DA0007-DA0032, # 3 Appendix DA0033-DA0072, # 4 Appendix DA0073-DA0112, # 5 Appendix DA0113-DA0152, # 6 Appendix DA0153-DA0192, # 7 Appendix DA0193-DA0232, # 8 Appendix DA0153-DA0192, # 7 Appendix DA0193-DA0232, # 8 Appendix DA0273-DA0272, # 9 Appendix DA0273-DA0312, # 10 Appendix DA0313-DA0352, # 11 Appendix DA0433-DA0472, # 14 Appendix DA0473-DA0512, # 15 Appendix DA0433-DA0472, # 14 Appendix DA0473-DA0512, # 15 Appendix DA0513-DA0521, # 16 Appendix DA0522-DA0563, # 17 Appendix SEALED - DA0564-DA0551, # 18 Appendix DA0552-DA0563, # 19 Appendix SEALED - DA0564-DA0566, # 20 Appendix DA0567-DA0573, # 21 Appendix SEALED - DA0574-DA0599, # 22 Appendix DA0667-DA0573, # 21 Appendix SEALED - DA0574-DA0599, # 22 Appendix DA0660-DA0604, # 23 Appendix DA0605-DA0609, # 24 Appendix DA0663-DA0667, # 30 Appendix SEALED - DA0635, # 29 Appendix DA0668-DA0667, # 30 Appendix SEALED - DA0635-DA0667, # 30 Appendix DA0638-DA0698, # 34 Appendix DA0668-DA0679, # 31 Appendix DA0671-DA0678, # 32 Appendix DA0679-DA0705, # 35 Appendix DA0688-DA0698, # 34 Appendix SEALED - DA0712-DA0714, # 37 Appendix DA0688-DA0698, # 34 Appendix SEALED - DA0712-DA0714, # 37 Appendix DA0715-DA0717, # 38 Appendix DA0715-DA0717, # 38 Appendix DA0715-DA0717, # 38 Appendix DA0741-DA0749, # 43 Appendix DA0750-DA0709, # 44 Appendix DA0773-DA0732, # 41 Appendix DA0769, # 44 Appendix DA0770-DA0781, (Rogowski, Patricia) (Entered: 06/25/2010)	
	D528	CLAIM CONSTRUCTION OPENING BRIEF Plaintiffs S.O.I.TEC Silicon on Insulator Technologies, S.A. and Commissariat a L'Energie Atomique's Opening Claim Construction Brief filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 06/25/2010)	
	D529	DECLARATION re <u>168</u> Claim Construction Opening Brief, Declaration of Marcus T. Hall in Support of Plaintiffs S.O.I.TEC Silicon on Insulator Technologies, S.A. and Commissariat a L'Energie Atomique's Opening Claim Construction Brief by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # <u>1</u> Certificate of Service)(Kraft, Denise) (Entered: 06/25/2010)	

EXAMINER	DATE CONSIDERED

Page 26 of 48

		Page 26 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT	·	
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuone	Nguven et al.

(use several s	niccto ii	AFF LICANT (5). Nguyet-Friuong Nguyeti et al.
EXAMINER INITIAL	(Includ	OTHER ART – NON PATENT LITERATURE DOCUMENTS le name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, sixum, catalog, etc.), date page(s), volume-issue number(s), bublisher, city and/or country where published.
	D530	APPENDIX re 167 Claim Construction Opening Brief, by MEMC Electronic Materials Inc (Attachments: # 1 Appendix DA-0001 - DA-0006, # 2 Appendix DA-0007 - DA-0032, # 3 Appendix DA-0033 - DA-0072, # 4 Appendix DA-0073 - DA-0112, # 5 Appendix DA-0113 - DA-0152, # 6 Appendix DA-0133 - DA-0192, # 7 Appendix DA-0130 - DA-0232, # B Appendix DA-0273 - DA-0312, # 10 Appendix DA-0313 - DA-0352, # 11 Appendix DA-0353 - DA-0392, # 12 Appendix DA-0353 - DA-0352, # 12 Appendix DA-0473, DA-04512, # 16 Appendix DA-0513 - DA-0512, # 16 Appendix DA-0512, # 16 Appendix DA-0513, PA-0512, # 16 Appendix DA-0513 - DA-0512, # 16 Appendix DA-0513 - DA-0512, # 16 Appendix DA-0513 - DA-0512, # 16 Appendix DA-0513 - DA-0513 - DA-0512, # 16 Appendix DA-0513 -
	D531	REDACTED VERSION of 175 Appendix by MEMC Electronic Materials Inc (Attachments: #1 Appendix DA0522-DA0545, #2 Appendix DA0546-DA0551, #3 Appendix DA0552-DA0563, #4 Appendix DA0567-DA0573, #6 Appendix DA0567-DA0573, #6 Appendix DA0567-DA0573, #6 Appendix DA0608-DA0609, #9 Appendix DA0610-DA0626, #10 Appendix DA0608-DA0609, #9 Appendix DA0610-DA0625, #110 Appendix DA0626-DA0634, #11 Appendix DA0635, #12 Appendix DA0636-DA0652, #13 Appendix DA0653-DA0657, #14 Appendix DA0658-DA0667, #15 Appendix DA0668-DA0670, #16 Appendix DA0678, #17 Appendix DA0678-DA0678, #18 Appendix DA0688-DA0669, #19 Appendix DA0679-DA0678, #18 Appendix DA0708-DA0711, #21 Appendix DA0712-DA0714, #22 Appendix DA0715-DA0717, #23 Appendix DA0718-DA0719, #24 Appendix DA072-DA0722, #25 Appendix DA0733-DA0732, #26 Appendix DA0733-DA0740, #27 Appendix DA0749, #28 Appendix DA0733-DA0740, #27 Appendix DA0741-DA0749, #28 Appendix DA0733-DA0740, #27 Appendix DA0741-DA0749, #28 Appendix DA0748-DA0769, #28 Ap
	D532	NOTICE of filing the following document(s) in paper format: Joint Appendix of Exhibits to Opening and Answering Claim Construction Briefs (1) Vol. I - JA0001 to JA0533. APPENDIX VOL L re 173 Notice of Filing Paper Documents(OVERSIZED DOCUMENT, ITEM ON FILE IN THE CLERKS OFFICE). (lid) (Entered: 06/28/2010).
	D533	NOTICE of filing the following document(s) in paper format: Joint Appendix of Exhibits to Opening and Answering Claim Construction Briefs (2) Vol. II - JA0534 to JA0930. APPENDIX VOL II. re 173 Notice of Filing Paper Documents(OVERSIZED DOCUMENT, ITEM ON FILE IN THE CLERKS OFFICE). (lid) (Entered: 06/28/2010).
	D534	NOTICE of filing the following document(s) in paper format: Joint Appendix of Exhibits to Opening and Answering Claim Construction Briefs (3) Vol. III – JA0931 to JA1502. APPENDIX VOL III. re 173 Notice of Filing Paper Documents(OVERSIZED DOCUMENT, ITEM ON FILE IN THE CLERKS OFFICE) (lid) (Entered: 06/28/2010) (2 parts).

EXAMINER	DATE CONSIDERED

Page 27 of 48

		Page 27 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT	·	
(use several sheets if necessary)	APPLICANT(S): Nguyet-Phuong	g Nguyen et al.

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D535	NOTICE of filing the following document(s) in paper format: Joint Appendix of Exhibits to Opening and Answering Claim Construction Briefs (4) Vol. IV – JA1503 to JA1510. APPENDIX VOL IV. re 173 Notice of Filing Paper Documents, (OVERSIZED DOCUMENT, ITEM ON FILE IN THE CLERKS OFFICE) (lid) (Entered: 06/28/2010).	
	D536	NOTICE of filing the following document(s) in paper format: Joint Appendix of Exhibits to Opening and Answering Claim Construction Briefs (5) Vol. V – JA1511 to JA2089 (2 parts).	
	D537	Vol. VI - JA2090 to JA2557. Original document(s) to be filed with the Clerk's Office. Notice filed by Denise Seastone Kraft on behalf of Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 06/25/2010).	
	D538	MOTION in Limine SOITEC/CEA Parties' Motion to Exclude The Expert Report of Dr. Pascal Bellon and Any Related Testimony - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Text of Proposed Order, # 2 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)	
	D539	MOTION for Partial Summary Judgment of Invalidity of the Asserted Aspar Patent Claims - filed by MEMC Electronic Materials Inc (Attachments: # 1 Text of Proposed Order, # 2 Certificate of Service)(Rogowski, Patricia) (Entered: 07/02/2010)	
	D540	OPENING BRIEF in Support re <u>186</u> MOTION in Limine SOITEC/CEA Parties' Motion to Exclude The Expert Report of Dr. Pascal Bellon and Any Related Testimony filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA.Answering Brief/Response due date per Local Rules is 7/19/2010. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)	
	D541	OPENING BRIEF in Support re <u>187</u> MOTION for Partial Summary Judgment of Invalidity of the Asserted Aspar Patent Claims filed by MEMC Electronic Materials IncAnswering Brief/Response due date per Local Rules is 7/19/2010. (Rogowski, Patricia) (Entered: 07/02/2010)	

EXAMINER	DATE CONSIDERED

Page 28 of 48

		Page 28 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuono	Nouven et al.

EXAMINER INITIAL	(Includ	OTHER ART – NON PATENT LITERATURE DOCUMENTS ie name of author, tild of the article (when appropriate), title of the item (book, magazine, journal, serial, sium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.
	D542	APPENDIX re 186 MOTION in Limine SOITEC/CEA Parties' Motion to Exclude The Expert Report of Dr. Pascal Bellon and Any Related Tastimony Plainfifs' Omnibus Appendix to Daubert Motion and Motions For Partial Summary Judgment Filed on July 2, 2010 by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: #1 Appendix VoI. IV of XIX, #2 Appendix VoI. IV of XIX, #4 Appendix VoI. VI of XIX, #4 Appendix VoI. VI of XIX, #5 Appendix VoI. VI of XIX, #6 Appendix VoI. XI of XIX, #7 Appendix VoI. XI of XIX, #8 Appendix VoI. XII of XIX, #9 Appendix VoI. XII of XIX, #10 Appendix VoI. XIV of XIX, #11 Appendix VoI. XIV of XIX, #12 Appendix VoI. XIV of XIX, #12 Appendix VoI. XIV of XIX, #13 Appendix VoI. XIV of XIX, #14 Appendix VoI. XIV of XIX, #15 Appendix VoI. XIV of XIX, #15 Appendix VoI. XIV of XIX, #16 Appendix VoI. XIV of XIX, #17 Appendix VoI. XIV of XIX, #18 Appendix VoI. XIV of XIX, #19 Appendi
	D543	MOTION for Summary Judgment of Non-Infringement - filed by MEMC Electronic Materials Inc (Attachments: # 1 Text of Proposed Order, # 2 Certificate of Service)(Rogowski, Patricia) (Entered: 07/02/2010)
	D544	MOTION for Partial Summary Judgment SOITEC/CEA Parties Motion For Partial Summary Judgment That The Patents in Sulf Satisfy The Written Description Requirement - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)
	D545	OPENING BRIEF in Support re <u>202</u> MOTION for Partial Summary Judgment SOITEC/CEA Parties Motion For Partial Summary Judgment That The Patents in Suit Satisfy The Written Description Requirement filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., IncAnswering Brief/Response due date per Local Rules is 7/19/2010. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)
	D546	MOTION for Partial Summary Judgment Plaintiffs' Motion For Partial Summary Judgment That The Certificate of Correction For the '396 Patent is Valid - flied by Commissaria a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)
	D547	OPENING BRIEF in Support re 204 MOTION for Partial Summary Judgment Plaintiffs' Motion For Partial Summary Judgment That The Certificate of Correction For the '396 Patent is Valid filled by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA.Answering Brief/Response due date per Local Rules is 7/19/2010, (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)

EXAMINER	DATE CONSIDERED

Page 20 of 48

		Page 29 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuon	g Nguyen et al.

EXAMINER INITIAL	(Includ	OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D548	MOTION for Partial Summary Judgment SOITEC/CEA Parties' Motion For Partial Summary Judgment That The Aspar Patents Are Not Invalid For Inequitable Conduct filled by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Text of Proposed Order, # 2 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)		
	D549	OPENING BRIEF in Support re 206 MOTION for Partial Summary Judgment SOITEC/CEA Parties' Motion For Partial Summary Judgment That The Aspar Patents Are Not Invalid For Inequitable Conduct filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., IncAnswering Brief/Response due date per Local Rules is 7/19/2010. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)		
	D550	MOTION for Partial Summary Judgment Plaintiffs' Motion For Partial Summary Judgment That The Bruel Patent Does Not Anticipate The Aspar Patents - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Text of Proposed Order, # 2 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)		
	D551	OPENING BRIEF in Support re 208 MOTION for Partial Summary Judgment Plaintiffs' Motion For Partial Summary Judgment That The Bruel Patent Does Not Anticipate The Aspar Patents filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA.Answering Brief/Response due date per Local Rules is 7/19/2010, (Attachments: #1 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)		
	D552	MOTION for Partial Summary Judgment SOITEC's Motion For Partial Summary Judgment of Invalidity of United States Patent No. 5,834,812 For Lack of Enablement - filed by SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Text of Proposed Order, # 2 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)		
	D553	OPENING BRIEF in Support re 210 MOTION for Partial Summary Judgment SOITEC's Motion For Partial Summary Judgment of Invalidity of United States Patent No. 5,834,812 For Lack of Enablement filed by SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc. Answering Brief/Response due date per Local Rules is 7/19/2010. (Attachments: #1 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)		

EXAMINER	DATE CONSIDERED

Page 30 of 48

			Page 30 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
		10/577,175	9905/40
			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	A	April 3, 2007	2813
STATEMENT			
(use several sheets if necessary)	APPLICANT(S): No	uvet-Phuona	Nouven et al.

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D554	MOTION for Partial Summary Judgment SOITEC's Motion For Partial Summary Judgment For Invalidity of Asserted Claims of United States Patent No. 5,834,812 in View of Prior Art - filed by SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: #1 Text of Proposed Order, #2 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)	
	D555	MOTION for Partial Summary Judgment That the Best Mode Requirement is Satisfied for the Claims of the '009 and '396 Patents - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Text of Proposed Order, # 2 Certificate of Service)(Reed, John) (Entered: 07/02/2010)	
	D556	OPENING BRIEF in Support re 212 MOTION for Partial Summary Judgment SOITEC's Motion For Partial Summary Judgment For Invalidity of Asserted Claims of United States Patent No. 5,834,812 in View of Prior Art filed by SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., IncAnswering Brief/Response due date per Local Rules is 7/19/2010. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 07/02/2010)	
	D557	OPENING BRIEF in Support re <u>213</u> MOTION for Partial Summary Judgment That the Best Mode Requirement is Satisfied for the Claims of the '009 and '396 Patents filed by SOITEC Silicon On Insulator Technologies SA.Answering Brief/Response due date per Local Rules is 7/19/2010. (Attachments: # 1 Certificate of Service)(Reed, John) (Entered: 07/02/2010)	
	D558	REDACTED VERSION of 200 Opening Brief in Support, by MEMC Electronic Materials Inc (Attachments: # 1 Certificate of Service)(Rogowski, Patricia) (Entered: 07/07/2/2015)	

EXAMINER	DATE CONSIDERED	
EXAMINEN	DATE CONSIDERED	

		Page 31 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT	·	
(use several sheets if necessary)	APPLICANT(S): Nguyet-Phuon	Nguven et al.

		ru zerati (e). Hguyet i muong ngayet ot un	
		OTHER ART. MON PATENT LITERATURE POCUMENTS	
EXAMINER	OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial,		
INITIAL		sium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.	
	D559	REDACTED VERSION of 201 Appendix by MEMC Electronic Materials Inc (Attachments: #1 Appendix MA0001 - MA0004, #2 Appendix MA0005 - MA0010, #3 Appendix MA0011 - MA0016, #4 Appendix MA0007 - MA0020, #5 Appendix MA0021 - MA0029, #6 Appendix MA0030 - MA0045, #7 Appendix MA0046 - MA0052, #8 Appendix MA0053 - MA0078, #9 Appendix MA0079 - MA0092, #10 Appendix MA0093 - MA0129, #11 Appendix MA0130 - MA0148, #12 Appendix MA0149 - MA0160, #13 Appendix MA0161 - MA0163, #14 Appendix MA0164 - MA0167, #15 Appendix MA0188 - MA0172, #16 Appendix MA0173 - MA0183, #17 Appendix MA0184 - MA0196, #18 Appendix MA0197 - MA0207, #19 Appendix MA0208 -	
		MA0241, # <u>20</u> Appendix MA0242 - MA0245, # <u>21</u> Appendix MA0246 - MA0249, # <u>22</u> Appendix MA0250 - MA0255, # <u>24</u> Appendix MA0253 - MA0265, # <u>24</u> Appendix MA0266 - MA0281, # <u>25</u> Appendix MA0286 - MA030312, # <u>26</u> Appendix MA0313 - MA0359, # <u>27</u> Appendix MA0360 - MA0365, # <u>28</u> Appendix MA0366, # <u>29</u> Appendix MA0367 - MA0400, # <u>30</u> Appendix MA0401 - MA0474, # <u>31</u> Appendix MA0475 - MA0483, # <u>32</u> Certificate)(Rogowski, Patricia) (Entered: 07/07/2010)	
	D560	REDACTED VERSION of 190 Appendix by MEMC Electronic Materials Inc (Attachments: # 1 Appendix MA0484 - MA0489, # 2 Appendix MA0490 - MA0515, # 3 Appendix MA0516 - MA0534, # 4 Appendix MA0535 - MA0541, # 5 Appendix MA0542 - MA0550, # 6 Appendix MA0565 - MA0568, # 9 Appendix MA0567 - MA0576, # 12 Appendix MA0564, # 8 Appendix MA0565 - MA0568, # 14 Appendix MA0570 - MA0577, # 10 Appendix MA0667, # 11 Appendix MA0677 - MA0601, # 12 Appendix MA0602 - MA0603, # 13 Appendix MA0604 - MA0605, # 14 Appendix MA0606 - MA0609, # 15 Appendix MA0610 - MA0612, # 16 Appendix MA0631 - MA0625, # 17 Appendix MA0621 - MA0626 - MA0689, # 18 Appendix MA0621 - MA0686, # 21 Appendix MA0631 - MA0626 - MA0688, # 18 Appendix MA0631 - MA0658, # 21 Appendix MA0701, # 22 Appendix MA0702 - MA0732, # 23 Appendix MA0733 - MA0742, # 24 Appendix MA0734 - MA0750, # 25 Appendix MA0751 - MA0750, # 25 Appendix MA0751 - MA0750, # 25 Appendix MA0751 - MA0750, # 26 Appendix MA0753 - MA0781, # 29 Appendix MA0888 - MA0884, # 30 Appendix MA0825 - MA0831, 1, # 31 Appendix MA0835 - MA0838, # 32 Appendix MA0839 - MA0884, # 33 Appendix MA0889 - MA0884, # 33 Appendix MA0889 - MA0887, # 36 Appendix MA0887 - MA0888, # 32 Appendix MA0889 - MA0887, # 36 Appendix MA0887 - MA0889, # 37 Appendix MA0885 - MA0887, # 38 Appendix MA0887 - MA0889, # 39 Appendix MA0887 - MA0889, # 38 Appendix MA0889 - MA0889, # 39 Appendix MA0889 - MA0889, # 30 Appendix MA0889 - MA	
	D561	REDACTED VERSION of 198 Opening Brief in Support,, SOITEC/CEA Parties' Opening Brief In Support Of Motion For Summary Judgment: Non-Infringement by Commissaria t a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 07/08/2010)	

EXAMINER	DATE CONSIDERED

		Page 32 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,17	5 9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 200	7 2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phu	ng Nguyen et al

(uoo oo roidi o		7 in Providing Control of Transport	
EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), dete page(s), volume-issue number(s), publisher, city and/or country where published.		
	D562	REDACTED VERSION of 197 SEALED MOTION for Summary Judgment SOITEC/CEA Parties' Motion For Summary Judgment: Non-Infringement (FILED UNDER SEAL)SEALED MOTION for Summary Judgment SOITEC/CEA Parties' Motion For Summary Judgment: Non-Infringement (FILED UNDER SEAL) SOITEC/CEA Parties' Motion For Summary Judgment: Non-Infringement by Commissaria a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 07/08/2010)	
	D563	REDACTED VERSION of 192 Appendix, Plaintiffs' Omnibus Appendix to Daubert Motion And Motions For Partial Summary Judgment Filed on July 2, 2010 - Volume VI of XIX by Commissariat a LEnergie Atomique, 80/ITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 07/09/2010)	
	D564	REDACTED VERSION of 193 Appendix, Plaintiffs' Omnibus Appendix to Daubert Motion And Motions For Partial Summary Judgment Filed on July 2, 2010 - Volume VIII of XIX by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 07/09/2010)	
	D565	REDACTED VERSION of 194 Appendix, Plaintiffs' Omnibus Appendix to Daubert Motion And Motions For Partial Summary Judgment Filed on July 2, 2010 - Volume X of XIX by Commissariat a LEnergie Atomique, 80/ITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 07/09/2010)	
	D566	REDACTED VERSION of 195 Appendix, Plaintiffs' Omnibus Appendix to Daubert Motion And Motions For Partial Summary Judgment Filed on July 2, 2010 - Volume XVII of XIX by Commissardia a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 07/09/2010)	
	D567	REDACTED VERSION of 196 Appendix, Plaintiffs' Omnibus Appendix to Daubert Motion And Motions For Partial Summary Judgment Filed on July 2, 2010 - Volume XIX of XIX by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 07/09/2010)	
	D568	CLAIM CONSTRUCTION ANSWERING BRIEF re 168 Claim Construction Opening Brief, filed by MEMC Electronic Materials Inc (Attachments: # 1 Certificate of Service)(Rogowski, Patricia) (Entered: 07/09/2010)	
	D569	APPENDIX re <u>228</u> Claim Construction Answering Brief by MEMC Electronic Materials Inc (Attachments: #1 Appendix DA0782, DA0783, #2 Appendix DA0784 - DA0785, #3 Appendix DA0786, #4 Appendix DA08787 - DA0810, #5 Appendix DA0811 - DA0834, #6 Appendix DA0835 - DA0845, #7 Appendix DA0846 - DA0855, #8 Certificate of Service)(Rogowski, Patricia) (Entered: 07/09/2010)	

EXAMINER	DATE CONSIDERED	

Page 33 of 48

		Page 33 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,1	75 9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 20	07 2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phu	ong Nguven et al.

		7 in Production Transport
EXAMINER INITIAL	(Includ	OTHER ART – NON PATENT LITERATURE DOCUMENTS le name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, sium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published. CLAIM CONSTRUCTION ANSWERING BRIEF re 168 Claim Construction Opening
	D370	Parief, 228 Claim Construction Answering Brief Plaintiffs S.O.I.TEC on Insulator Technologies, S.A. And Commissariat A Energie Atomique's Answering Claim Construction Brief filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: #_1 Certificate of Service)(Kraft, Denise) (Entered: 07/09/2010)
	D571	APPENDIX re 230 Claim Construction Answering Brief, Appendix to Plaintiffs S.O.I.TEC On Insulator Technologies, S.A. And Commissariat A Energie Atomique's Answering Claim Construction Brief by Commissariat a Lenergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Appendix PA-0001 - PA- 0050, # 2 Appendix PA-0051 - PA-0083, # 3 Certificate of Service)(Kraft, Denise) (Entered: 07/09/2010)
	D572	REDACTED VERSION of 193 Appendix, Joint Appendix of Exhibits to Opening and Answering Claim Construction Briefs Volume IV of VI by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Kraft, Denise) (Entered: 07/12/2010)
	D573	REDACTED VERSION of 170 Exhibit to a Document, Exhibit A to Declaration of Marcus T. Hall in Support of Plaintiffs S.O.I.TEC Silicon on Insulator Technologies, S.A. and Commissariat a L'Energie Atomique's Opening Claim Construction Brief by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Kraft, Denise) (Entered: 07/12/2010)
	D574	REDACTED VERSION of <u>171</u> Exhibit to a Document, Exhibit B to Declaration of Marcus T. Hall in Support of Plaintiffs S.O.I.TEC Silicon on Insulator Technologies, S.A. and Commissariat a L'Energie Atomique's Opening Claim Construction Brief by Commissariat a L'Energie Atomique, SOITEC Silicon On Insulator Technologies SA. (Kraft, Denise) (Entered: 07/12/2010)
	D575	REDACTED VERSION of <u>172</u> Exhibit to a Document, Exhibit C to Declaration of Marcus T. Hall in Support of Plaintiffs S.O.I.TEC Silicon on Insulator Technologies, S.A. and Commissariat a L'Energie Atomique's Opening Claim Construction Brief by Commissariat a L'Energie Atomique, SOITEC Silicon On Insulator Technologies SA. (Kraft, Denise) (Entered: 07/12/2010)
	D576	ANSWERING BRIEF in Opposition re 186 MOTION in Limine SOITEC/CEA Parties' Motion to Exclude The Expert Report of Dr. Pascal Bellon and Any Related Testimony filed by MEMC Electronic Materials Inc. Reply Brief due date per Local Rules is 7/29/2010. (Rogowski, Patricia) (Entered: 07/19/2010)

DATE CONSIDERED	

		Page 34 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT	·	
(use several sheets if necessary)	APPLICANT(S): Nguvet-Phuong Nguven et al.	

EXAMINER INITIAL	(Includ	OTHER ART – NON PATENT LITERATURE DOCUMENTS In name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, sium, catalog, etc), date page(s), volume-issue number(s), bublisher, city andro country where published.
	D577	ANSWERING BRIEF in Opposition re 208 MOTION for Partial Summary Judgment Plaintiffs' Motion For Partial Summary Judgment That The Bruel Patent Does Not Anticipate The Aspar Patents filed by MEMC Electronic Materials IncReply Brief due date per Local Rules is 7/29/2010. (Rogowski, Patricia) (Entered: 07/19/2010)
	D578	ANSWERING BRIEF in Opposition re 202 MOTION for Partial Summary Judgment SOITEC/CEA Parties Motion For Partial Summary Judgment That The Patents in Suit Satisfy The Written Description Requirement filed by MEMC Electronic Materials IncReply Brief due date per Local Rules is 7/29/2010. (Rogowski, Patricia) (Entered: 07/19/2010)
	D579	ANSWERING BRIEF in Opposition re 204 MOTION for Partial Summary Judgment Plaintiffs' Motion For Partial Summary Judgment That The Certificate of Correction For the '396 Patent is Valid filed by MEMC Electronic Materials IncReply Brief due date per Local Rules is 7/29/2010. (Rogowski, Patricia) (Entered: 07/19/2010)
	D580	ANSWERING BRIEF in Opposition re 210 MOTION for Partial Summary Judgment SOITEC's Motion For Partial Summary Judgment of Invalidity of United States Patent No. 5,834,812 For Lack of Enablement filed by MEMC Electronic Materials IncReply Brief due date per Local Rules is 7/29/2010. (Rogowski, Patricia) (Entered: 07/19/2010)
	D581	ANSWERING BRIEF in Opposition re 212 MOTION for Partial Summary Judgment SOITEC's Motion For Partial Summary Judgment For Invalidity of Asserted Claims of United States Patent No. 5,834,812 in View of Prior Art filed by MEMC Electronic Materials IncReply Brief due date per Local Rules is 7/29/2010. (Rogowski, Patricia) (Entered: 07/19/2010)
	D582	APPENDIX re 247 Answering Brief in Opposition., Appendix To Plaintiffs' Answering Brief In Opposition To Defendant's Motion For Partial Summary Judgment Of Invalidity Of The Asserted Aspar Claims (PA-1103 - PA-1156) by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Exhibit PA-1103 - PA-1109 - FILED UNDER SEAL, # 2 Exhibit PA-1110 - PA-1118 - FILED UNDER SEAL, # 3 Exhibit PA-1119 - PA-1130 - FILED UNDER SEAL, # 4 Exhibit PA-1131 - PA-1143 - FILED UNDER SEAL, # 5 Exhibit PA-1144 - PA-1156, # 6 Certificate of Service)(Kraft, Denise) (Entered: 07/19/2010)
	D583	APPENDIX re 250 Answering Brief in Opposition, Appendix to Plaintiffs' Answering Brief in Opposition to Defendant's Motion For Summary Judgment of Non-Infringement by Commissariat a Lenergie Atomique, SOITEC Silicon On Insulator Technologies. SA. (Attachments: #1 Exhibit PA-1190 - PA-1191, #2 Certificate of Service)(Kraft, Denise) (Entered: 07/19/2010)

EXAMINER	DATE CONSIDERED
1.2 % - 1%	and the control of th

Page 35 of 48

		Page 35 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT	·	
(use several sheets if necessary)	APPLICANT(S): Nguyet-Phuong Nguyen et al.	

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS (include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), outhure-Issue number(s), publisher, vity and/or country where published.		
	D584	REDACTED VERSION of <u>241</u> Answering Brief in Opposition, to Plaintiffs' Motion for Partial Summary Judgment that the Best Mode Requirement is Satisfied for the Claims of the '009 and '396 Patents by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 07/26/2010)	
	D585	REDACTED VERSION of 249 Answering Brief in Opposition, to Plaintiffs' Motion for Summary Judgment on the Infringement of U.S. Patent No. 5,834,812 by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 07/26/2010)	
	D586	REDACTED VERSION of <u>253</u> Answering Brief in Opposition, to Plaintiffs' Motion for Partial Summary Judgment that the Aspar Patents Are Not Invalid for Inequitable Conduct by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 07/26/2010)	
	D587	REDACTED VERSION of 240 Appendix by MEMC Electronic Materials Inc (Attachments: #1 Appendix MA0932 - MA0985, #2 Appendix MA0986 - MA1039.22, #3 Appendix MA1040 - MA1144, #4 Appendix MA1145 - MA1200, #5 Appendix MA1039.22, #3 Appendix MA1040 - MA1144, #4 Appendix MA1145 - MA1200, #5 Appendix MA1399 - MA1547, #8 Appendix MA1648 - MA1687, #9 Appendix MA1688, #10 Appendix MA1684 - MA1627, #9 Appendix MA1628 - MA1693, #10 Appendix MA1694 - MA1953, #11 Appendix MA2164 - MA2127, #12 Appendix MA2128 - MA2206, #13 Appendix MA2207 - MA2253, #14 Appendix MA2254 - MA2274 - MA2337, #17 Appendix MA2338 - MA2342, #18 Appendix MA2343 - MA2346, #19 Appendix MA2347 - MA2354, #10 Appendix MA2347 - MA2354	
	D588	REDACTED VERSION of <u>261</u> Answering Brief in Opposition, to Plaintiffs' Motion for Partial Summary Judgment that the Best Mode Requirement is Satisfied for the Claims of the '009 and '396 Patents (CORRECTED VERSION OF D.I. 241) by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 07/26/2010)	
	D589	REDACTED VERSION of <u>250</u> Answering Brief in Opposition, to Soitec's Brief in Opposition to Defendant's Motion For Summary Judgment of Non-Infringement by Commissaria a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # <u>1</u> Certificate of Service)(Kraft, Denise) (Entered: 07/26/2010)	
	D590	REDACTED VERSION of 247 Answering Brief in Opposition,, to Plaintiffs' Answering Brief In Opposition To Defendant's Motion For Partial Summary Judgment Of In validity Of The Asserted Aspar Claims by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: #1 Certificate of Service)(Kraft, Denise) (Entered: 07/26/2010)	

EXAMINER	DATE CONSIDERED	

Page 36 of 48

		Page 36 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT	·	
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuon	n Nguven et al.

(use several s	sileets ii	The Cessary) AFFLICANT (3). Inguyet-Frittonig inguyeti et al.
EXAMINER INITIAL	(Includ	OTHER ART – NON PATENT LITERATURE DOCUMENTS In name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, sium, catalog, etc.), date page(p), volume-issue number(s), bublisher, city and/or country where published.
	D591	REDACTED VERSION of <u>254</u> Appendix, to Appendix To Plaintiffs' Answering Brief In Opposition To Defendant's Motion For Partial Summary Judgment Of Invalidity Of The Asserted Aspar Claims (PA-1103 - PA-1143 by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Kraft, Denise) (Entered: 07/26/2010)
	D592	REDACTED VERSION of <u>251</u> Appendix, to Appendix to Plaintiffs' Answering Brief in Opposition to Defendant's Motion For Summary Judgment of Non-Infringement by Commissaria a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Kraft, Denise) (Entered: 07/26/2010)
	D593	REPLY BRIEF re <u>204</u> MOTION for Partial Summary Judgment Plaintiffs' Motion For Partial Summary Judgment That The Certificate of Correction For the '396 Patent is Valid Reply Brief in Support of Plaintiffs' Motion For Partial Summary Judgment That The Certificate of Correction For the '396 Patent is Valid filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 07/30/2010)
4	D594	DECLARATION re <u>268</u> Reply Brief, Declaration of Marcus T. Hall in Support of Reply Brief in Support of Plaintiffs' Motion For Partial Summary Judgment That The Certificate of Correction For the '396 Patent is Valid by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Exhibit A, # 2 Certificate of Service)(Kraft, Denise) (Entered: 07/30/2010)
	D595	APPENDIX re <u>268</u> Reply Brief, Omnibus Appendix to Plaintiffs' Reply Briefs in Support of Plaintiffs' Daubert Motion and Motions For Partial Summary Judgment (PA-1192 - PA-1261) by Commissaria a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # <u>1</u> Exhibit PA-1199 - PA-1204, # <u>2</u> Exhibit PA-1205 - PA-1206, # <u>3</u> Exhibit PA-1206. # <u>4</u> Exhibit PA-1231 - PA-1237, # <u>5</u> Exhibit PA-1238 - PA-1246- PA-1257, # <u>7</u> Exhibit PA-1258 - PA-1261, # <u>8</u> Certificate of Service)(Kraft, Denise) (Entered: 07/30/2010)
	D596	REPLY BRIEF re 210 MOTION for Partial Summary Judgment SOITEC's Motion For Partial Summary Judgment of Invalidity of United States Patent No. 5,834,812 For Lack of Enablement Reply Brief in Support of SOITEC's Motion For Partial Summary Judgment of Invalidity of United States Patent No. 5,834,812 For Lack of Enablement filled by SOITEC U.S.A., Inc (Attachments: # 1 Certificate of Service) Kraft, Denise) (Entered: 07/30/2010)

EXAMINER	DATE CONSIDERED

Page 37 of 48

			Page 37 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
		10/577,175	9905/40
			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE		April 3, 2007	2813
STATEMENT			
(use several sheets if necessary)	APPLICANT(S): N	lauvet-Phuona	Nguven et al.

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D597	REPLY BRIEF re 212 MOTION for Partial Summary Judgment SOITEC's Motion For Partial Summary Judgment For Invalidity of Asserted Claims of United States Patent No. 5,834,812 in View of Prior Art Reply Brief in Support of SOITEC's Motion For Partial Summary Judgment For Invalidity of Asserted Claims of United States Patent No. 5,834,812 in View of Prior Art filed by SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: #1 Exhibit A, #2 Exhibit B, #3 Certificate of Service)(Kraft, Denise) (Entered: 07/30/2010)	
	D598	REPLY BRIEF re 202 MOTION for Partial Summary Judgment SOITEC/CEA Parties Motion For Partial Summary Judgment That The Patents in Suit Satisfy The Written Description Requirement Reply Brief in Support of SOITEC/CEA Parties Motion For Partial Summary Judgment That The Patents in Suit Satisfy The Written Description Requirement filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 07/30/2010)	
	D599	REDACTED VERSION of <u>269</u> Appendix, TO REPLY BRIEF IN SUPPORT OF MEMC's MOTION FOR PARTIAL SUMMARY JUDGMENT OF INVALIDITY OF THE ASSERTED ASPAR PATENT CLAIMS by MEMC Electronic Materials Inc (Attachments: # 1 Appendix Table of Contents, # 2 Appendix MA2453_MA2479, # <u>3</u> Certificate of Service)(Rogowski, Patricia) (Entered: 08/03/2010)	
	D600	REDACTED VERSION of <u>273</u> Appendix REPLY BRIEF IN SUPPORT OF MEMC'S MOTION FOR SUMMARY JUDGMENT OF NON-INFRINGEMENT by MEMC Electronic Materials Inc., Clatachments: #1 Appendix Table of Contents, #2 Appendix MA2352 - MA2361, #3 Appendix MA2362 - MA2371, #4 Appendix MA2372 - MA2381, #5 Appendix MA2382 - MA2391, #6 Appendix MA2392 - MA2399, #7 Appendix MA24040, #8 Appendix MA2405 - MA2422, #9 Appendix MA2423 - MA2445, #10 Appendix MA2426 - MA247, #11 Appendix MA2428 - MA2430, #12 Appendix MA2413 - MA2440, #13 Appendix MA2441 - MA2448, #14 Appendix MA2445, #15 Appendix MA2452 - MA2452, #15 Appendix MA2452 - MA2452, #16 Certificate of Service)(Rogowski, Patricia) (Entered: 08/03/2010)	
	D601	REDACTED VERSION of <u>267</u> Reply Brief IN SUPPORT OF MEMC's MOTION FOR PARTIAL SUMMARY JUDGMENT OF INVALIDITY OF THE ASSERTED ASPAR PATENT CLAIMS by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 08/03/2010)	
	D602	REDACTED VERSION of <u>271</u> Reply Brief IN SUPPORT OF MEMC's MOTION FOR SUMMARY JUDGMENT OF NON-INFRINGEMENT by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 08/03/2010)	

EXAMINER	DATE CONSIDERED	

Page 38 of 48

		Page 38 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT	·	
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuon	n Nguven et al.

(400 00101411		The Elevation (b). Highly of Theory Highly of the
EXAMINER INITIAL OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal symposium, catalog, etc.), date page(s), obume-issue number(s), publisher, city and/or country where		
	D603	REDACTED VERSION of <u>274</u> Appendix, Omnibus Appendix to Plaintiffs' Reply Briefs in Support of Plaintiffs' Daubert Motion and Motions For Partial Summary Judgment (PA-1192 - PA-1198 and PA-1207 - PA-1230 Filed Under Seal) by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Kraft, Denise) (Entered: 08/06/2010)
	D604	REDACTED VERSION of <u>277</u> Reply Brief, in Support of SOITEC/CEA Parties' Motion to Exclude The Expert Report of Dr. Pascal Bellon and Any Related Testimony by Commissaria a LEnergie Atonique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 08/06/2010)
	D605	REDACTED VERSION of <u>278</u> Reply Brief., in Support of SOITEC/CEA Parties' Motion For Summary Judgment: Non-Infringement (Filed Under Seal) by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 08/06/2010)
	D606	REDACTED VERSION of <u>279</u> Reply Brief,, in Support of Plaintiffs' Motion for Partial Summary Judgment That the Best Mode Requirement is Satisfied for the Claims of the '009 and '396 Patents (Filed Under Seal) by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # <u>1</u> Certificate of Service)(Kraft, Denise) (Entered: 08/06/2010)
	D607	REDACTED VERSION of <u>281</u> Reply Brief, in Support of Plaintiffs' Motion For Partial Summary Judgment That The Bruel Patent Does Not Anticipate The Aspar Patents (Filed Under Seal) by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # <u>1</u> Certificate of Service)(Kraft, Denise) (Entered: 08/06/2010)
	D608	REDACTED VERSION of <u>282</u> Reply Brief., in Support of SOITEC/CEA Parties' Motion For Partial Summary Judgment That The Aspar Patents Are Not Invalid For Inequitable Conduct (Filed Under Seal) by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # <u>1</u> Certificate of Service)(Kraft, Denise) (Entered: 08/06/2010)
	D609	NOTICE OF SERVICE of CD of documents MEMC0782194-MEMC0782500 and FH-1 0001 - FH-8 0067 by MEMC Electronic Materials Inc(Rogowski, Patricia) (Entered: 09/16/2010)
	D610	REDACTED VERSION of 301 SEALED MOTION for Reconsideration Request to Modify Protective Order by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 09/24/2010)

EXAMINER	DATE CONSIDERED

Page 39 of 48

			Page 39 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
		10/577,175	9905/40
			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE		April 3, 2007	2813
STATEMENT			
(use several sheets if necessary)	APPLICANT(S): N	Iguyet-Phuong	Nguyen et al.

EXAMINER INITIAL	(Includ	OTHER ART – NON PATENT LITERATURE DOCUMENTS ie name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, sium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.
	D611	REDACTED VERSION of 302 Declaration, of Michael L. Brody in Support of Motion to Reconsider Request to Modify Protective Order by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 09/24/2010)
	D612	REDACTED VERSION of 303 Exhibit to a Document Exhibit A to Michael L. Brody in Support of Motion to Reconsider Request to Modify Protective Order by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Kraft, Denise) (Entered: 09/24/2010)
	D613	REDACTED VERSION of 304 Exhibit to a Document Exhibit B to Michael L. Brody in Support of Motion to Reconsider Request to Modify Protective Order by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Kraft, Denise) (Entered: 09/24/2010)
	D614	REDACTED VERSION of 305 Exhibit to a Document Exhibit C to Michael L. Brody in Support of Motion to Reconsider Request to Modify Protective Order by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Kraft, Denise) (Entered: 09/24/2010)
	D615	REDACTED VERSION of 306 Exhibit to a Document Exhibit D to Michael L. Brody in Support of Motion to Reconsider Request to Modify Protective Order by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Kraft, Denise) (Entered: 09/24/2010)
	D616	Proposed Pretrial Order [Proposed] Joint Pretrial Order (FILED UNDER SEAL) by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Exhibit 1 (Sealed), # 2 Exhibit 2A (Sealed), # 3 Exhibit 2B (Sealed), # 4 Exhibit 3A (Sealed), # 5 Exhibit 3B (Sealed), # 6 Exhibit 4B (Sealed), # 10 Exhibit 4B (Sealed), # 11 Exhibit 6A (Sealed), # 12 Exhibit 6B (Sealed), # 13 Exhibit 7B (Sealed), # 14 Exhibit 7B (Sealed), # 15 Certificate of Service)(Kraft, Denise) (Entered: 10/07/2010)
	D617	Proposed Voir Dire by MEMC Electronic Materials Inc (Attachments: # 1 Certificate of Service)(Rogowski, Patricia) (Entered: 10/08/2010)
	D618	VERDICT SHEET by MEMC Electronic Materials Inc (Attachments: # 1 Certificate of Service)(Rogowski, Patricia) (Entered: 10/08/2010)
	D619	Proposed Voir Dire by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 10/08/2010)

EXAMINER	DATE CONSIDERED

Page 40 of 48

			Page 40 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
		10/577,175	9905/40
			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE		April 3, 2007	2813
STATEMENT			
(use several sheets if necessary)	APPLICANT(S): I	Nauvet-Phuona	Nguven et al.

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D620	VERDICT SHEET by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 10/08/2010)	
	D621	Proposed Jury Instructions by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 10/08/2010)	
	D622	Proposed Jury Instructions by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 10/08/2010)	
	D623	REDACTED VERSION of 315 Proposed Pretrial Order,, Redacted Version of [Proposed] Joint Pretrial Order by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: #1 Exhibit 1, #2 Exhibit 2A, #3 Exhibit 2B, #4 Exhibit 3A, #5 Exhibit 3B, #6 Exhibit 4A, #7 Exhibit 4B, #8 Exhibit 4C, #9 Exhibit 5A, #10 Exhibit 5B, #11 Exhibit 6A, #12 Exhibit 6A, #12 Exhibit 7A, #14 Exhibit 7B, #15 Certificate of Service)(Kraft, Denise) (Entered: 10/13/2010)	
	D624	MEMORANDUM OPINION. Signed by Judge Sue L. Robinson on 10/13/2010. (nmf) (Entered: 10/13/2010)	
	D625	ORDER denying 141 Motion for Discovery; denying 186 Motion in Limine; granting in part and denying in part 187 Motion for Partial Summary Judgment granting 197 Motion for Summary Judgment; granting 199 Motion for Summary Judgment; granting 202 Motion for Partial Summary Judgment; granting 202 Motion for Partial Summary Judgment; denying 206 Motion for Partial Summary Judgment; granting in part and denying in part 208 Motion for Partial Summary Judgment; denying 210 Motion for Partial Summary Judgment; denying 210 Motion for Partial Summary Judgment; granting in part and denying in part 213 Motion for Partial Summary Judgment; Signed by Judge Sue L. Robinson on 10/13/2010. (nmf) (Entered: 10/13/2010)	
	D626	MEMORANDUM ORDER re: claim construction. Signed by Judge Sue L. Robinson on 10/13/2010. (nmf) (Entered: 10/13/2010) ORAL ORDER by Judge Sue L. Robinson on 10/14/2010 that the responses to the issues raised in the exhibits to the joint pre-trial order are to be stricken from the record. (These filings, formerly D.I. Nos. 318 and 323 have been deleted from the docket.) (nmf) (Entered: 10/14/2010)	

EXAMINER	DATE CONSIDERED

Page 41 of 48

		Page 41 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuor	g Nguyen et al.

(use several s	neets ii	necessary) APPLICANT(5): nguyet-Phuong nguyen et al.
EXAMINER INITIAL	(Includ sympo D627	OTHER ART – NON PATENT LITERATURE DOCUMENTS let name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, settine, catalog, etc.), date pagely, volume-issue number(s), bublisher, city and/or country where published. AMENDED ORDER denying 141 Motion for Discovery, denying 188 Motion in Limine; granting in part and denying in part 187 Motion for Partial Summary Judgment; granting 192 Motion for Summary Judgment; granting 192 Motion for Summary Judgment; granting 192 Motion for Partial Summary Judgment; granting 202 Motion for Partial Summary Judgment; denying 204 Motion for Partial Summary Judgment; granting in part and denying in part 208 Motion for Partial Summary Judgment; denying 210 Motion for Partial Summary Judgment; denying 210 Motion for Partial Summary Judgment; denying 210 Motion for Partial Summary Judgment; Summary Judgment; denying 210 Motion for Partial Summary Judgment. Signed by Judge Sue L. Robinson on 10/14/2010. (nmf) (Entered: 10/14/2010) Minute Entry for proceedings held before Judge Sue L. Robinson - Final Pretrial Conference held on 10/14/2010. (Court Reporter V. Gunning.) (nmf) (Entered: 10/15/2010) SO ORDERED, re 315 Proposed Pretrial Order. Signed by Judge Sue L. Robinson on 10/14/2010. (nmf) (Entered: 10/15/2010)
	D628 MOTION for Reargument re 327 Memorandum and Order - Reargument of Claim Construction of One Claim Term of U.S. Patent 6,809,009 - filed by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 10/18/2010)	
	D629	SECOND AMENDED ORDER re: 325 denying 141 Motion for Discovery; denying 186 Motion in Limine; granting in part and denying in part 187 Motion for Partial Summary Judgment; granting 197 Motion for Summary Judgment; granting 199 Motion for Summary Judgment **with respect to the '484 patent and with respect to its current process, and denied in other respects; granting 202 Motion for Partial Summary Judgment; denying 204 Motion for Partial Summary Judgment; denying 205 Motion for Partial Summary Judgment; granting in part and denying in part 208 Motion for Partial Summary Judgment; denying 210 Motion for Partial Summary Judgment; denying 210 Motion for Partial Summary Judgment; denying 211 Motion for Partial Summary Judgment; denying 212 Motion for Partial Summary Judgment; denying 212 Motion for Partial Summary Judgment, Signed by Judge Sue L. Robinson on 10/19/2010. (nmf) (Entered: 10/19/2010)
	D630	MEMORANDUM ORDER granting 329 MOTION for Reargument re 327 Memorandum and Order - Reargument of Claim Construction of One Claim Term of U.S. Patent 6,809,009. Signed by Judge Sue L. Robinson on 10/19/2010. (nmf) (Entered: 10/19/2010)
	D631	STIPULATION MEMC's Declaratory Judgment counterclaim asserting invalidity of United States Reissued Patent No. 39,484 in Civil Action No. 1:08-292-SLR is dismissed without prejudice by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (nmf,). (Entered: 10/21/2010)

EXAMINER	DATE CONSIDERED

Page 42 of 48

		Page 42 of 48
SERIAL NO.		CASE NO.
	10/577,175	9905/40 (BIF116533US)
FILING DATE		GROUP ART UNIT
	April 3, 2007	2813
APPLICANT(S): Nguyet-Phuong Nguyen et al.		
NER OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), yolume-issue number(s), publisher, city and/or country where published.		
norandum and O	rder, 327 Mem	orandum and Order,
325 Memorandum Opinion by Commissariat a LEnergie Atomique, SOITEC Silicon		
	APPLICANT(S) ATENT LITERATU propriate), title of the unumber(s), publish norandum and O	10/577,175 FILING DATE April 3, 2007 APPLICANT(S): Nguyet-Phuong ATENT LITERATURE DOCUMEN propriate), title of the item (book, magaz ue number(s), publisher, city andor cou norandum and Order, 327 Mem

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D632	STIPULATION of Fact re 331 Memorandum and Order, 327 Memorandum and Order, 325 Memorandum Opinion by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 10/21/2010)	
	D633	Letter to The Honorable Sue L. Robinson from Denise Seastone Kraft regarding Mutually agreed upon narrowing of the issues for trial - re 333 Stipulation, 332 Stipulation, (Kraft, Denise) (Entered: 10/21/2010) CORRECTING ENTRY: The pdf of D.I. 332 has been replaced with the correct pdf of the stipulation per request of filer. (nmf) (Entered: 10/22/2010) SO ORDERED, re 333 Stipulation filed by SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc., Commissariat a LEnergie Atomique, 332 Stipulation, filed by SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc., Commissariat a LEnergie Atomique, 332 Stipulation, filed by SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc., Commissariat a LEnergie Atomique. Signed by Judge Sue L. Robinson on 10/22/2010. (nmf) (Entered: 10/22/2010)	
	D634	Voir Dire Questions. Read in Open Court 10/25/2010.(nmf) (Entered: 10/25/2010)	
	D635	Preliminary Jury Instructions. Read in Open Court 10/25/2010. (nmf) (Entered: 10/25/2010) Minute Entry for proceedings held before Judge Sue L. Robinson: Jury Trial Day 1 held on 10/25/2010. (Court Reporter Valerie Gunning, Brian Gaffigan.) (dlk) (Entered: 10/26/2010)	
	D636	PLAINTIFF'S BENCH MEMORANDUM. Filed in Court 10/26/2010. (nmf) (Entered: 10/26/2010) Minute Entry for proceedings held before Judge Sue L. Robinson - Jury Trial (Day 2) held on 10/26/2010. (Court Reporter Valerie Gunning, Kevin Maurer.) (dlk) (Entered: 10/26/2010) Minute Entry for proceedings held before Judge Sue L. Robinson - Jury Trial - Day 3, held on 10/27/2010. (Court Reporter Valerie Gunning/Kevin Maurer.) (mms) (Entered: 10/27/2010)	
	D637	STATEMENT – BENCH MEMORANDUM SUPPORTING MEMC'S PROFFER OF ADMISSIONS BY SOITEC IN PRIOR LAWSUIT INVOLVING THE! 564 PATENT submitted at trial by MEMC Electronic Materials Inc (Attachments: # 1 Exhibit A)(Rogowski, Patricia) (Entered: 10/28/2010) Minute Entry for proceedings held before Judge Sue L. Robinson - Jury Trial - Day 4 held on 10/28/2010. (Court Reporter Valerie Gunning/Kevin Maurer.) (nms) (Entered: 11/01/2010)	
	D638	Final Jury Instructions read in open Court by Judge Robinson. (Iid) (Entered: 11/01/2010) Minute Entry for proceedings held before Judge Sue L. Robinson - Jury Trial held on 11/1/2010. (DAY 5) (Court Reporter V. Gunning.) (Iid) (Entered: 11/02/2010) Minute Entry for proceedings held before Judge Sue L. Robinson - Jury Trial completed on 11/2/2010. (DAY 6) (Court Reporter V. Gunning.) (Iid) (Entered: 11/02/2010)	

EXAMINER	DATE CONSIDERED

Page 43 of 48

		Page 43 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuon	d Nauven et al

(use several sneets it necessary) APPLICANT(5). Nguyet-Phuong Nguyen et al.			
EXAMINER INITIAL			
	D639	REDACTED VERSION of 342 Jury Verdict. (lid) (Entered: 11/02/2010)	
	D640	STATEMENT Bench Memorandum in Support of Plaintiffs' Motion For Judgment as a Matter of Law of No Unenforceability of the '009 Patent Due To Inequitable Conduct submitted at trial by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 11/02/2010)	
	D641	ANSWERING BRIEF in Opposition re 301 SEALED MOTION for Reconsideration Request to Modify Protective Order (MEMC'S OPPOSITION TO PLAINTIFFS' MOTION FOR REARGUMENT RE: MODIFICATION OF THE PROTECTIVE ORDER) filed by MEMC Electronic Materials IncReply Brief due date per Local Rules is 11/22/2010, (Attachments: #1 Exhibit 1 through 5, #2 Certificate of Service)(Rogowski, Patricia) (Entered: 11/12/2010)	
	D642	JUDGMENT in favor of defendant MEMC Electronic Materials, Inc. and against plaintiffs S.O.I.TEC Silicon On Insulator Technologies, S.A. and Commisseriat A LEnergie Atomique et aux Energies Alternatives as to the 812 patent. IT IS FURTHER ORDERED that judgment be and is hereby entered in favor of plaintiffs S.O.I.TEC Silicon On Insulator Technologies, S.A. and Commisseriat A LEnergie Atomique et aux Energies Alternatives and against defendant MEMC Electronic Materials, Inc. as to the 009 patent. Signed by Judge Sue L. Robinson on 11/15/2010. (nmf) (Entered: 11/15/2010)	
	D643	STIPULATION Setting Post-Trial Briefing Schedule re 348 Judgment,, by Commissariat a LEnergie Atomique, MEMC Electronic Materials Inc., SOITEC Silicon On Insulator Technologies SA. (Rogowski, Patricia) (Entered: 11/15/2010)	
	D644	MOTION for Reargument re 348 Judgment., (MEMCS MOTION FOR REARGUMENT OF THE COURTS ORDER RE: THE UNENFORCEABILITY OF THE 009 PATENT) - filed by MEMC Electronic Materials Inc. (Attachments: #1 Exhibit 1)(Rogowski, Patricia) (Entered: 11/16/2010) SO ORDERED- re 349 Stipulation. Set POST TRIAL Briefing Schedule: (Opening Brief due 12/8/2010., Answering Brief due 12/29/2010., Reply Brief due 11/2/2010.). Signed by Judge Sue L. Robinson on 11/17/2010. (lid) (Entered: 11/17/2010)	
	D645	MOTION for Leave to File Reply in Support of Plaintiff's Motion for Reargument - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: #1 Text of Proposed Order, #2 Certificate of Service)(Kraft, Denise) (Entered: 11/23/2010)	

EXAMINER	DATE CONSIDERED

Page 44 of 48

		Page 44 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuor	g Nguven et al.

(use several s	sneets if	necessary) APPLICANT(S): Nguyet-Phuong Nguyen et al.	
EXAMINER INITIAL	NITIAL (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D646	OPENING BRIEF in Support re 301 SEALED MOTION for Reconsideration Request to Modify Protective Order, 351 MOTION for Leave to File Reply in Support of Plaintiff's Motion for Reargument filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA.Answering Brief/Response due date per Local Rules is 12/10/2010, (Attachments: # 1 Appendix A, # 2 Certificate of Service)(Kraft, Denise) (Entered: 11/23/2010)	
	D647	STIPULATION TO EXTEND TIME Respond to MEMC's Motion for Reargument of the Court's Order Re: Unenforceability of the '009 Patent to December 3, 2010 - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 11/24/2010) SO ORDERED- re 353 STIPULATION TO EXTEND TIME. Set Briefing Schedule: re 350 MOTION for Reargument re 348 Judgment, (Answering Brief due 12/3/2010.). Signed by Judge Sue L. Robinson on 11/30/2010. (lid) (Entered: 11/30/2010)	
	D648	STIPULATION TO EXTEND TIME to file Motions and Opening Post-Trial Briefs to December 13, 2010 - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 12/03/2010)	
	D649	REPLY BRIEF re 350 MOTION for Reargument re 348 Judgment, (MEMCS MOTION FOR REARGUMENT OF THE COURTS ORDER RE: THE UNENFORCEABILITY OF THE 009 PATENT) Plaintiffs' Opposition to MEMC's Motion For Reargument of the Courts Order Re: The Unenforceability of the '009 Patent filed by Commissariat a Lenergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: #1 Exhibit A, #2 Certificate of Service) (Kraft, Denise) (Entered: 12/03/2010) SO ORDERED- re 354 STIPULATION TO EXTEND TIME. Set Briefing Schedule: (POST TRIAL Opening Brief due 12/13/2010.). Signed by Judge Sue L. Robinson on 12/6/2010. (lid) (Entered: 12/06/2010)	
	D650	EXHIBIT re 355 Reply Brief, Exhibit B to Plaintiffs' Opposition to MEMC's Motion For Reargument of the Court's Order Re: The Unenforceability of the '009 Patent by Commissaria a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 12/06/2010)	
	D651	ANSWERING BRIEF in Opposition re 351 MOTION for Leave to File Reply in Support of Plaintiff's Motion for Reargument filed by MEMC Electronic Materials IncReply Brief due date per Local Rules is 12/20/2010. (Rogowski, Patricia) (Entered: 12/10/2010)	

EXAMINER	DATE CONSIDERED

Page 45 of 48

			Page 45 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
	10/577,	175	9905/40
			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 20	007	2813
STATEMENT			
(use several sheets if necessary)	APPLICANT(S): Nguyet-Phuong Nguyen et al.		

		The Electric of Highly of Hidding Highly of the and	
EXAMINER INITIAL			
	D652	STIPULATION TO EXTEND TIME Stipulation and Order for Plaintiffs to file Motions and Opening Post-Trial Briefs to December 14, 2010 - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 12/13/2010)	
	D653	MOTION for Judgment as a Matter of Law - MEMC'S RENEWED MOTION FOR JUDGMENT AS A MATTER OF LAW OR IN THE ALTERNATIVE FOR A NEW TRIAL - filed by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 12/13/2010)	
	D654	OPENING BRIEF in Support re 359 MOTION for Judgment as a Matter of Law-MEMC'S RENEWED MOTION FOR JUDGMENT AS A MATTER OF LAW OR IN THE ALTERNATIVE FOR A NEW TRIAL filed by MEMC Electronic Materials IncAnswering Brief/Response due date per Local Rules is 12/30/2010. (Attachments: # 1 Exhibit 1, # 2 Certificate of Service)(Rogowski, Patricia) (Entered: 12/13/2010)	
	D655	MOTION for Judgment as a Matter of Law Plaintiffs' Renewed Motion For Judgment As A Matter of Law Or In The Alternative For A New Trial - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Text of Proposed Order, # 2 Certificate of Service)(Kraft, Denise) (Entered: 12/14/2010)	
	D656	OPENING BRIEF in Support re 361 MOTION for Judgment as a Matter of Law Plaintiffs' Renewed Motion For Judgment As A Matter of Law Or In The Alternative For A New Trial filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA.Answering Brief/Response due date per Local Rules is 1/3/2011. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 12/14/2010)	
	D657	MOTION For Injunctive Relief Plaintiffs' Motion For Injunctive Relief And To Lift Stay on Damages Discovery - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA. (Attachments: # 1 Text of Proposed Order, # 2 Certificate of Service)(Kraft, Denise) (Entered: 12/14/2010)	
	D658	STIPULATION TO EXTEND TIME due date for Answering and Reply Post-Trial Briefs to January 7, 2011 for Answering Brief and January 21, 2011 for Reply Brief - filed by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 12/15/2010) SO ORDERED- re 365 STIPULATION TO EXTEND TIME. Set Briefing Schedule: (Answering Post trial Brief due 1/7/2011., Reply post trial Brief due 1/21/2011.). Signed by Judge Sue L. Robinson on 12/16/2010. (lid) (Entered: 12/17/2010)	
	D659	STIPULATION TO EXTEND TIME Post-Trial Answering Briefs to January 12, 2011 - filed by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 01/06/2011)	

EXAMINER	DATE CONSIDERED

Page 46 of 48

		Page 46 of 48
FORM PTO-1449	SERIAL NO.	CASE NO.
	10/577,175	9905/40
		(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813
STATEMENT		
(use several sheets if necessary)	APPLICANT(S): Nauvet-Phuono	Nguven et al.

(use several s	niccio ii	Hecessary) AFT Elecant (6): Nguyet-Fridong Nguyeti et al.		
EXAMINER INITIAL	R OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), burdue-issue number(s), publisher, city and/or country where published.			
	D660	NOTICE of Appearance by Aleine Michelle Porterfield on behalf of Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc. (Attachments: # 1 Certificate of Service)(Porterfield, Aleine) (Entered: 01/07/2011)		
	D661	Joint STIPULATION TO EXTEND TIME Post-trial Answering Briefs and Post-trial Reply Briefs to January 14, 2011 and January 28, 2011 - filed by MEMC Electronic Materials Inc (Rogowski, Patricia) (Entered: 01/12/2011)		
	D662	ANSWERING BRIEF in Opposition re 359 MOTION for Judgment as a Matter of Law-MEMC'S RENWED MOTION FOR JUDGMENT AS A MATTER OF LAW OR IN THE ALTERNATUSE FOR A NEW TRIAL filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc. Reply Brief due date per Local Rules is 1/24/2011. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 01/14/2011).		
	D663	ANSWERING BRIEF in Opposition re 361 MOTION for Judgment as a Matter of Law Plaintiffs' Renewed Motion For Judgment As A Matter of Law Or In The Alternative For A New Trial (MEMCS ANSWERING BRIEF IN OPPOSITION TO PLAINTIFFS RENEWED MOTION FOR JUDGMENT AS A MATTER OF LAW OR IN THE ALTERNATIVE FOR A NEW TRIAL) filed by MEMC Electronic Materials IncReply Brief due date per Local Rules is 1/24/2011. (Attachments: # 1 Certificate of Service)(Rogowski, Patricia) (Entered: 01/14/2011).		
	D664	DECLARATION re <u>378</u> Answering Brief in Opposition, (DECLARATION OF ROBERT M. EVANS, JR. IN SUPPORT OF MEMCS OPPOSITION TO PLAINTIFFS RENEWED MOTION FOR JUDGMENT AS A MATTER OF LAW OR IN THE ALTERNATIVE FOR A NEW TRIAL) by MEMC Electronic Materials inc (Attachments: # 1 Exhibit 1, # 2 Exhibit 2, # 3 Certificate of Service)(Rogowski, Patricia) (Entered: 01/14/2011)		
	D665	REDACTED VERSION of <u>376</u> Answering Brief in Opposition, to Plaintiffs' Motion for Injunctive Relief and to Lift Stay on Damages Discovery by MEMC Electronic Materials. IncAttachments: # <u>1</u> Certificate of Servico)(Regewski, Patricla) (Enterod: 01/20/2011)		
	D666	REDACTED VERSION of <u>377</u> Appendix to MEMC's Answering Brief in Opposition to Plaintiffs' Motion for Injunctive Relief and to Lift Stay on Damages Discovery by MEMC Electronic Materials Inc. (Attachments: # <u>1</u> Exhibit 1-7, # <u>2</u> Exhibit 8, # <u>3</u> Exhibit 9, # <u>4</u> Exhibit 10, # <u>5</u> Exhibit 11, # <u>6</u> Exhibit 12-13, # <u>7</u> Exhibit 14, # <u>8</u> Exhibit 15, # <u>9</u> Exhibit 16, # <u>10</u> Exhibit 17, # <u>11</u> Exhibit 18, # <u>12</u> Exhibit 19, # <u>13</u> Certificate of Service)(Rogowski, Patricia) (Entered: 01/20/2011)		

EXAMINER	DATE CONSIDERED

Page 47 of 48

		Page 47 of 48	
FORM PTO-1449	SERIAL NO.	CASE NO.	
	10/577,175	9905/40	
		(BIF116533US)	
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE	GROUP ART UNIT	
APPLICANT'S INFORMATION DISCLOSURE	April 3, 2007	2813	
STATEMENT			
(use several sheets if necessary)	APPLICANT(S): Nguyet-Phuong Nguyen et al.		

(use several sheets if necessary)				
EXAMINER INITIAL	(Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.			
	D667 Joint STIPULATION TO EXTEND TIME of Post-Trial Reply Briefs to Tuesday, February 1, 2011 - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 01/28/2011)			
	D668 Joint STIPULATION TO EXTEND TIME of Post-Trial Reply Briefs to Friday, Febri 4, 2011 - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulate Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 01/31/2011)			
Damages Discovery by Commissariat a LEnergie Átomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Exhibit A, # 2 Exhibit B, # 3 Exhibit C, # 4 Exhibit D, # 5 Exhibit E, # 6 Exhibit F, # 7 Exhibit C,		Opening Brief in Support of Plaintiffs' Motion For Injunctive Relief And To Lift Stay on Damages Discovery by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Exhibit A, # 2 Exhibit B, # 3 Exhibit C, # 4 Exhibit D, # 5 Exhibit E, # 6 Exhibit F, # 7 Exhibit G, # 8 Exhibit H, # 9 Exhibit I, # 10 Exhibit J, # 11 Exhibit K, # 12 Exhibit L, # 13 Exhibit M, # 14 Exhibit N, # 15 Exhibit O, # 16 Exhibit P, # 17 Exhibit Q, # 18 Exhibit R, # 19		
	D670 REPLY BRIEF re 359 MOTION for Judgment as a Matter of Law - MEMC'S RENEWED MOTION FOR JUDGMENT AS A MATTER OF LAW OR IN THE ALTERNATIVE FOR A NEW TRIAL filed by MEMC Electronic Materials Inc (Attachments: # 1 Certificate of Service)(Rogowski, Patricia) (Entered: 02/04/2011			
D671 REPLY BRIEF re 361 MOTION for Judgment as a Matter of Law Plaintiffs' Renew Motion For Judgment As A Matter of Law Or In The Alternative For A New Trial file by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 02/04/2011)				
	D672	DECLARATION re 387 Reply Brief, Declaration of Michael L. Brody in Support of Reply Brief In Support of Plaintiffs' Renewed Motion For Judgment as a Matter of Law or In The Alternative For a New Trial by Commissariat a LEnergle Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Exhibit A, # 2 Certificate of Service)(Kraft, Denise) (Entered: 02/04/2011)		
	D673	MOTION to Strike 386 Reply Brief, Motion By Plaintiffs' To Strike Reply Brief In Support of MEMC's Renewed Motion For Judgment as a Matter of Law or, In The Alternative, a New Trial (D.I. 386) - filed by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 02/08/2011)		

EXAMINER	DATE CONSIDERED

Page 48 of 48

			Page 48 of 48
FORM PTO-1449	SERIAL NO.		CASE NO.
	10/57	7,175	9905/40
			(BIF116533US)
LIST OF PATENTS AND PUBLICATIONS FOR	FILING DATE		GROUP ART UNIT
APPLICANT'S INFORMATION DISCLOSURE	April 3	, 2007	2813
STATEMENT			
(use several sheets if necessary) APPLICANT(S): Nguyet-Phuong Nguyen et al.			Nguven et al.

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.		
	D674	OPENING BRIEF in Support re 390 MOTION to Strike 386 Reply Brief, Motion By Plaintiffs' To Strike Reply Brief in Support of MEMC's Renewed Motion For Judgment as a Matter of Law or, In The Alternative, a New Trial (D.I. 386) MOTION to Strike 386 Reply Brief, Motion By Plaintiffs' To Strike Reply Brief in Support of MEMC's Renewed Motion For Judgment as a Matter of Law or, In The Alternative, a New Trial (D.I. 386) filled by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc. Answering Brief/Response due date per Local Rules is 2/25/2011. (Attachments: # 1 Certificate of Service)(Kraft, Denise) (Entered: 02/08/2011)	
	D675	DECLARATION re 391 Opening Brief in Support, Declaration of Marcus T. Hall in Support of Plaintiffs' Opening Brief in Support of Motion to Strike Reply Brief in Support of Motion to Strike Reply Brief in Support of MEMC's Renewed Motion For Judgment as a Matter of Law or, In The Alternative, a New Trial (D.I. 386) by Commissariat a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc., (Attachments: # 1 Exhibit A, # 2 Certificate of Service)(Kraft, Denise) (Entered: 02/08/2011)	
	D676	REDACTED VERSION of 389 Reply Brief, Redacted Version of Reply Brief in Support of Plaintiffs' Motion For Injunctive Relief And To Lift Stay on Damages Discovery by Commissaria a LEnergie Atomique, SOITEC Silicon On Insulator Technologies SA, SOITEC U.S.A., Inc (Kraft, Denise) (Entered: 02/09/2011)	

EXAMINER /Daniel Luke/	DATE CONSIDERED	08/09/2011